

# Digital Integrated Circuits (83-313)

## Lecture 3: MOSFET Modeling

27 April 2020




Emerging Nanoscaled  
Integrated Circuits and Systems Labs



Bar-Ilan University  
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# Lecture Content



1 Basic MOS Models


2 Advanced MOS Models


3 VT Revisited


4 Simulating Variation

5 Leakage

Basic MOS Models

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Advanced MOS Models

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Threshold Voltage Revisited

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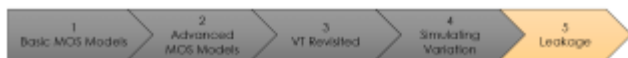
5 Leakage

Simulating Variation

Process Corners and Monte Carlo Simulation

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Leakage in NanoScaled Transistors

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# Basic MOS Models

# TCAD vs. Compact Models

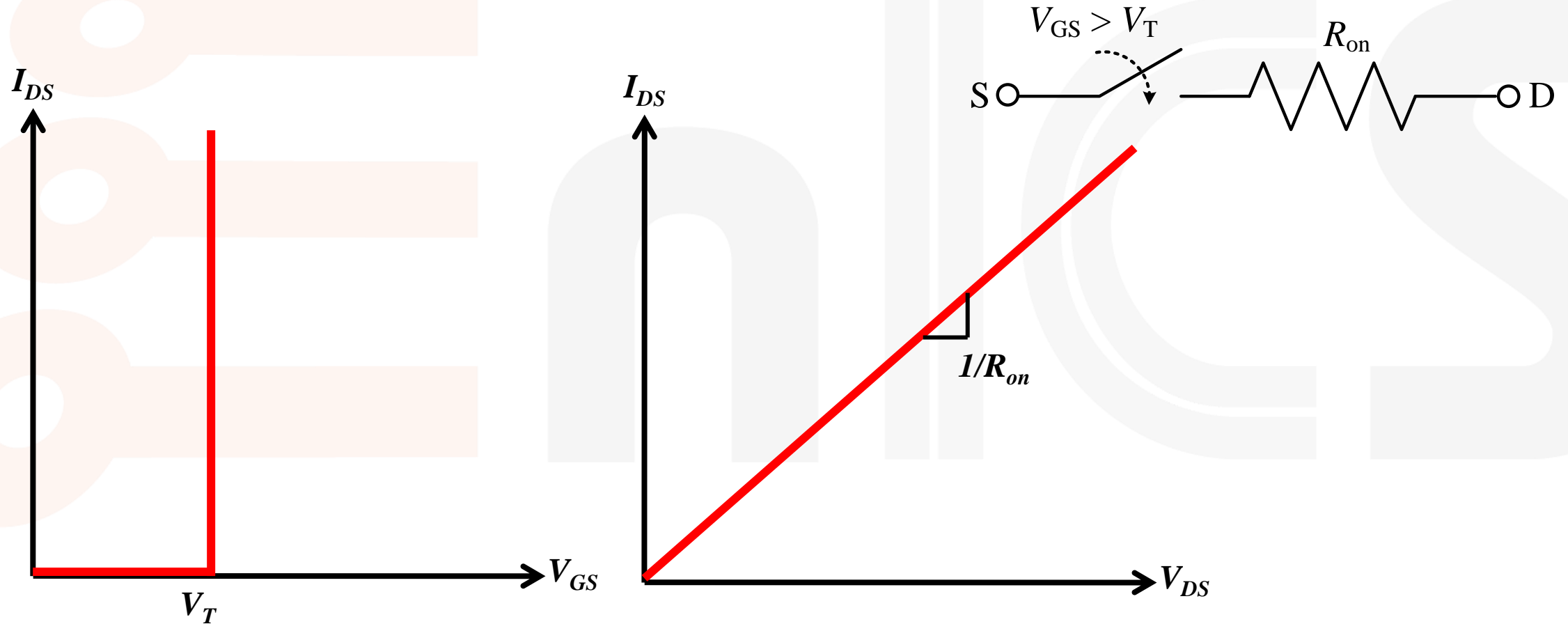
- Technology CAD (**TCAD**) is a simulation environment for accurately simulating device behavior:
  - Provide a process “recipe” and device layout
  - Produce IV or CV curves through device simulator
  - Used to predict device and process physics
  - Takes 1hr-1day per IV curve and 100s MB RAM per transistor
- Compact models (a.k.a. **SPICE models** or ECAD) are simple models used for circuit simulation
  - Provide a set of equations that SPICE uses to calculate IV or CV curves
  - Should take <100us per IV curve and a few KB per transistor
  - Usually extracted empirically from measurements

TCAD is too **slow** and **memory hungry** to be used for circuit simulation!

SPICE uses **compact models** for calculating device behavior

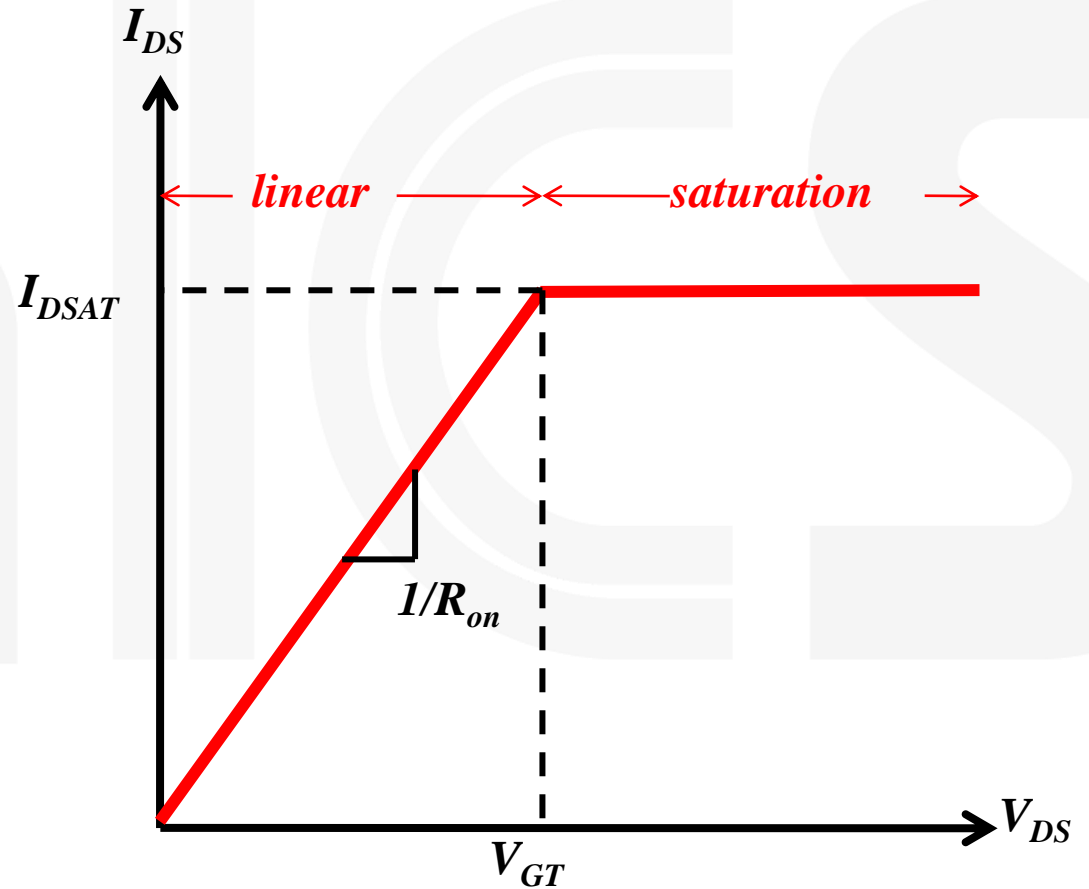
# Switch Model

- The most simple MOSFET model is the **Switch Model**.



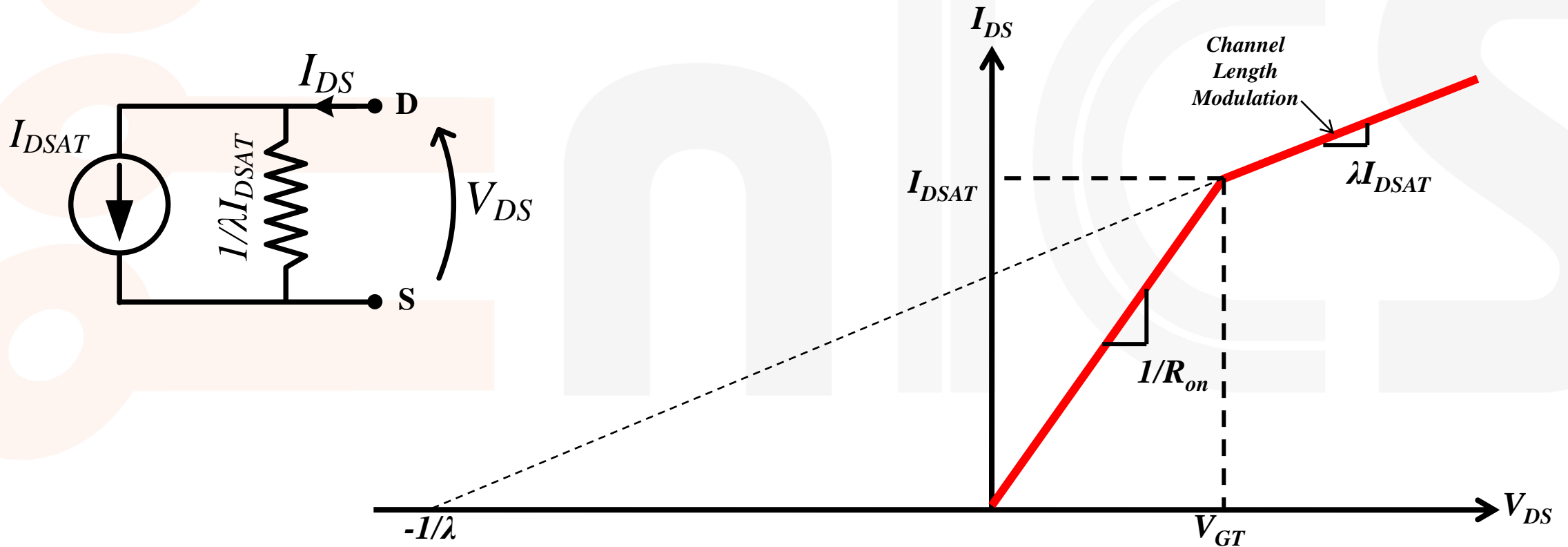
# The Piece-Wise Linear Model

- As we know, when the channel **pinches off**, the current **saturates**.
- This can be depicted with the simple **Piece-Wise Linear Switch Model**



# Adding Channel Length Modulation

- **Channel Length Modulation** modeled as a finite output resistance, causes a saturation current dependence on  $V_{DS}$ .



# Square Law (Shockley) Model

- To get a more accurate model, we already are familiar with the **Shockley** or **Square Law Model**.
- Current is just charge times velocity, so at any point,  $x$ , along the channel:

$$I_D(x) = -v(x)Q(x)Wdx$$

- We found that charge can be approximated as:

$$Q(x) = -C_{ox} [V_{GS} - V_{CS}(x) - V_T]$$

- And the velocity is the mobility times the electrical field:

$$v(x) = -\mu E(x) = \mu_n \frac{dV}{dx}$$



# Square Law (Shockley) Model

- So we get:

$$I_D dx = \mu_n C_{ox} W (V_{GS} - V - V_T) dV$$

- And integrating from source to drain, we get

$$I_{DS} = \int_0^L I_D dx = \int_0^{V_{DS}} \mu_n C_{ox} W (V_{GS} - V - V_T) dV = \mu_n C_{ox} \frac{W}{L} V_{DS} \left( V_{GS} - V_T - \frac{1}{2} V_{DS} \right)$$

- At pinch-off ( $V_{DS} = V_{GS} - V_T$ ), the voltage over the channel is constant, so we get:

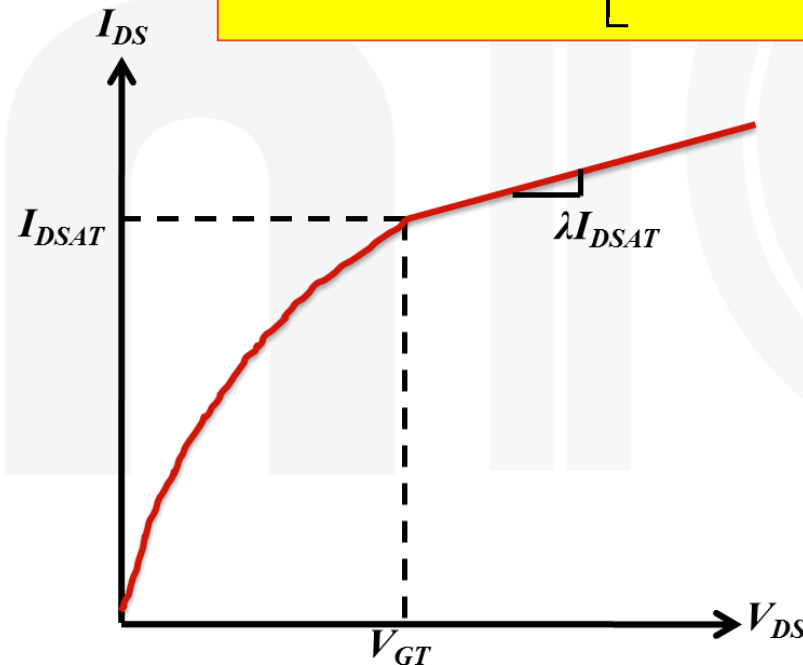
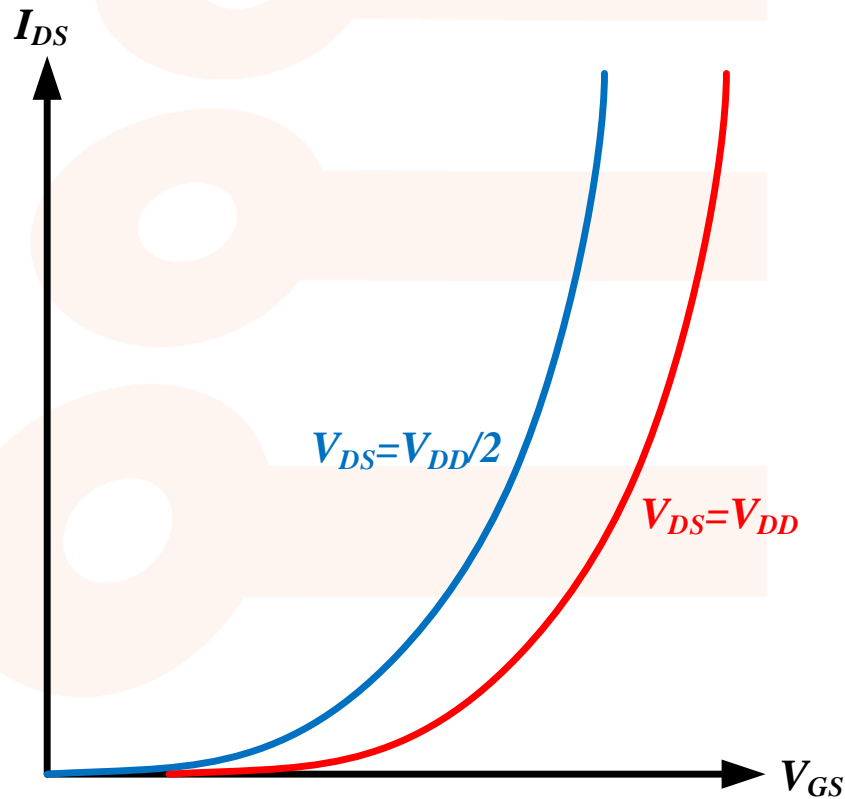
$$I_{DSAT} = \mu_n C_{ox} \frac{W}{2L} (V_{GS} - V_T)^2$$

- This is where the “**Square-Law**” name comes from.

# Square Law (Shockley) Model

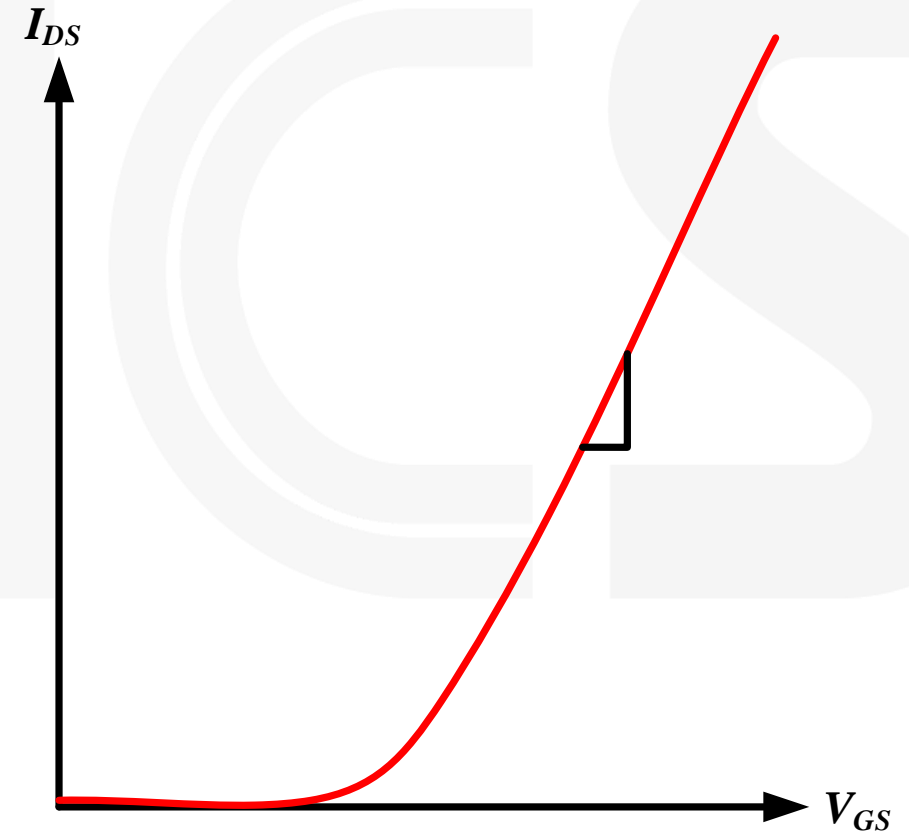
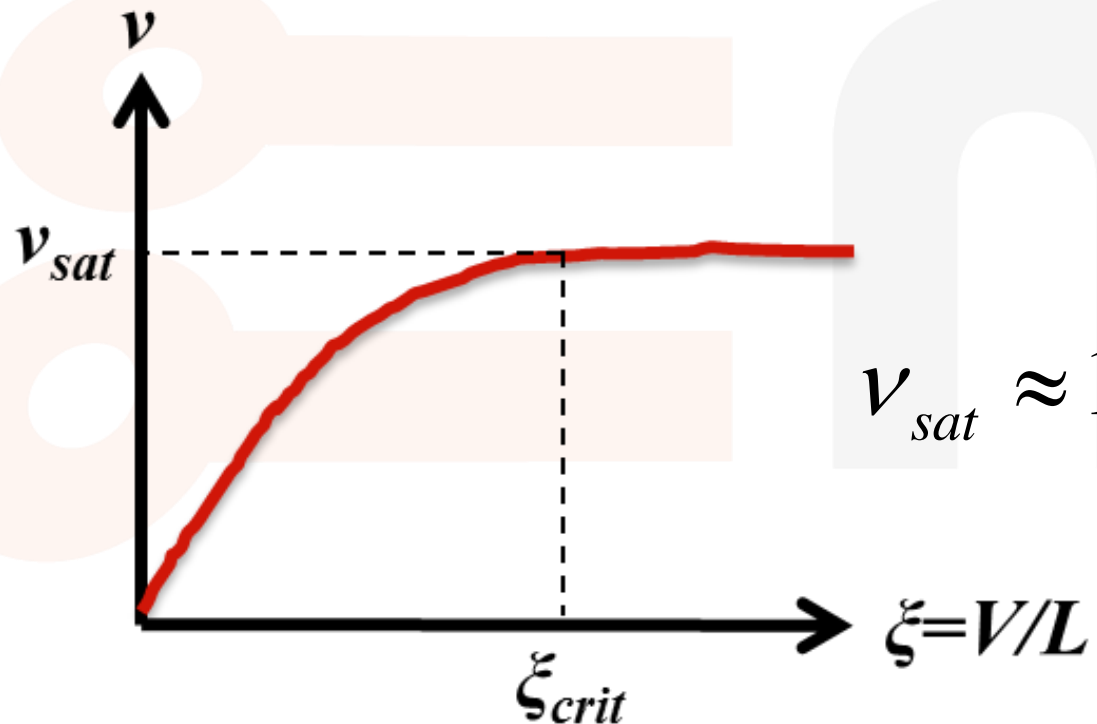
- Replacing  $V_{DS}$  with  $V_{DSeff} = \min(V_{GS} - V_T, V_{DS})$  we get:

$$I_{DS} = \mu_n C_{ox} \frac{W}{L} \left[ (V_{GS} - V_T) V_{DSeff} - \frac{V_{DSeff}^2}{2} \right] (1 + \lambda V_{DS})$$



# The Velocity Saturation Model

- However, when looking at a short channel device, we see a linear dependence on  $V_{GS}$ .
- This can be attributed to **Velocity Saturation**.



# The Velocity Saturation Model

- A good approximation of the mobility curve is:

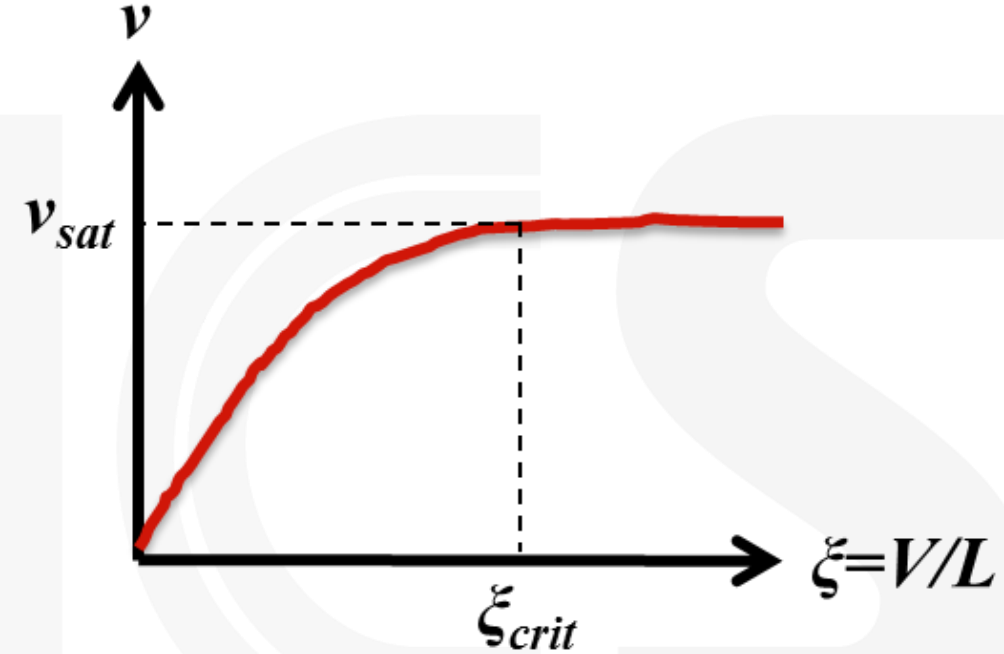
$$v = \begin{cases} \frac{\mu \xi}{1 + \xi / \xi_{crit}} & \xi < \xi_{crit} \\ v_{sat} & \xi > \xi_{crit} \end{cases}$$

- For continuity:

$$\xi_{crit} = \frac{2v_{sat}}{\mu}$$

- After integration, we get:

$$I_{DS} = \frac{\mu_n C_{ox}}{1 + \frac{V_{DS}}{\xi_{crit} L}} \frac{W}{L} \left[ (V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right]$$



# The Velocity Saturation Model

- This is hard to use, but we can reach an important conclusion.

- We found that:

$$I_{DS} = \frac{\mu_n C_{ox}}{1 + \frac{V_{DS}}{\xi_{crit} L}} \frac{W}{L} \left[ (V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

- And we know that for a velocity saturated device:

$$I_{DS} = W C_{ox} (V_{GS} - V_{DSAT} - V_T) v_{sat}$$

- Equating, we get:

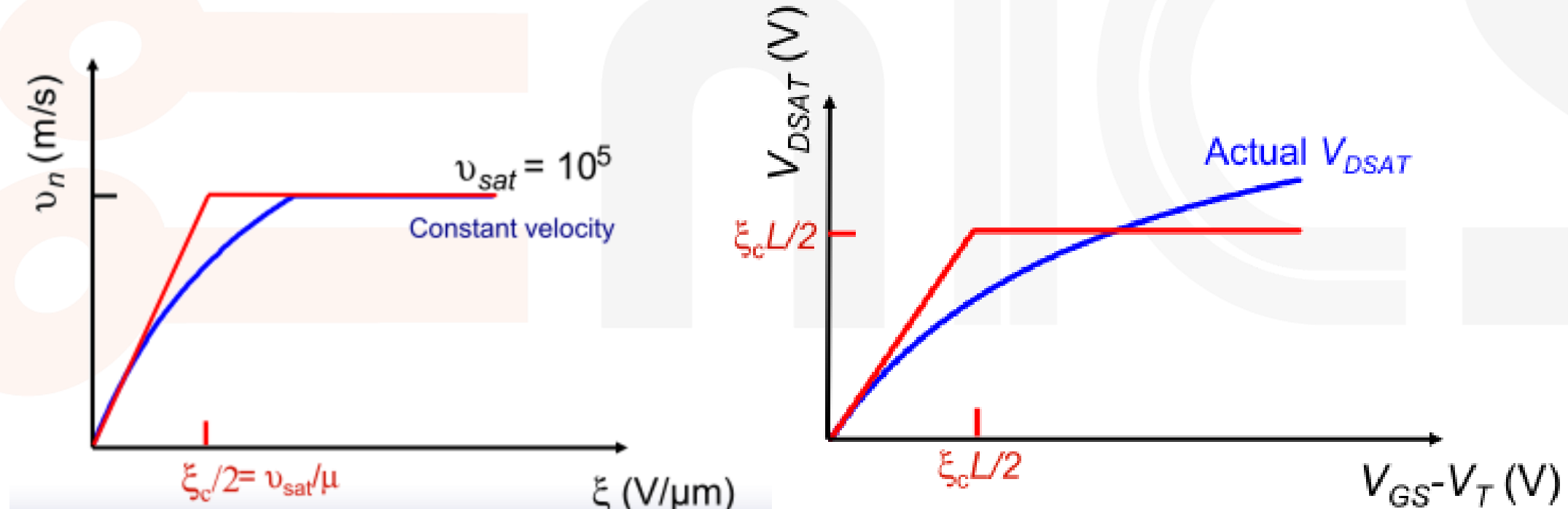
$$V_{DSAT} = \frac{(V_{GS} - V_T) \xi_{crit} L}{(V_{GS} - V_T) + \xi_{crit} L}$$

$$V_{DSAT} (\xi_{crit} L \gg V_{GT}) = V_{GS} - V_T \Rightarrow \text{pinch off}$$

$$V_{DSAT} (\xi_{crit} L \ll V_{GT}) = \xi_{crit} L \Rightarrow \text{vel sat}$$

# The Unified Model for Hand Analysis

- A few simple estimations will make the **V-Sat model** more user-friendly:
  - The mobility is piecewise linear, saturating at  $\xi > \xi_{\text{crit}}/2$
  - $V_{\text{DSAT}}$  is piecewise linear, saturating at  $V_{\text{DSAT}} = \xi_{\text{crit}} L/2$ , when  $V_{\text{GT}} > \xi_{\text{crit}} L/2$



# The Unified Model for Hand Analysis

- This brings us to the **Unified Model**:

$$I_{DS} = \mu_n C_{ox} \frac{W}{L} \left[ (V_{GS} - V_T) V_{DSeff} - \frac{V_{DSeff}^2}{2} \right] (1 + \lambda V_{DS})$$

$$V_{DSeff} = \min(V_{GS} - V_T, V_{DS}, V_{DSAT})$$

$$V_{DSAT} = \frac{\xi_{crit} L}{2} \quad \xi_{crit} = \frac{2v_{sat}}{\mu}$$



# Advanced MOS Models



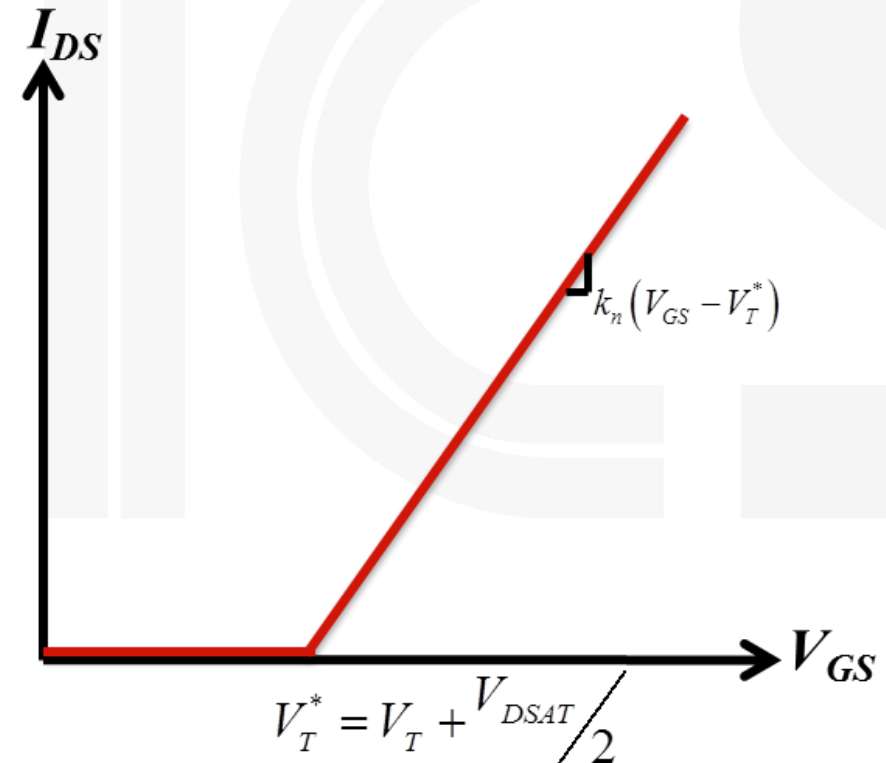
# VT\* Model

- Sometimes we want to use a really simple model.
- We can assume that if the transistor is on, it's **velocity saturated**.

$$I_{DS} = k_n \left[ (V_{GS} - V_T) V_{DSAT} - \frac{V_{DSAT}^2}{2} \right] =$$

$$= k_n \left[ \left( V_{GS} - \underbrace{\left( V_T + \frac{V_{DSAT}}{2} \right)}_{V_T^*} \right) V_{DSAT} \right]$$

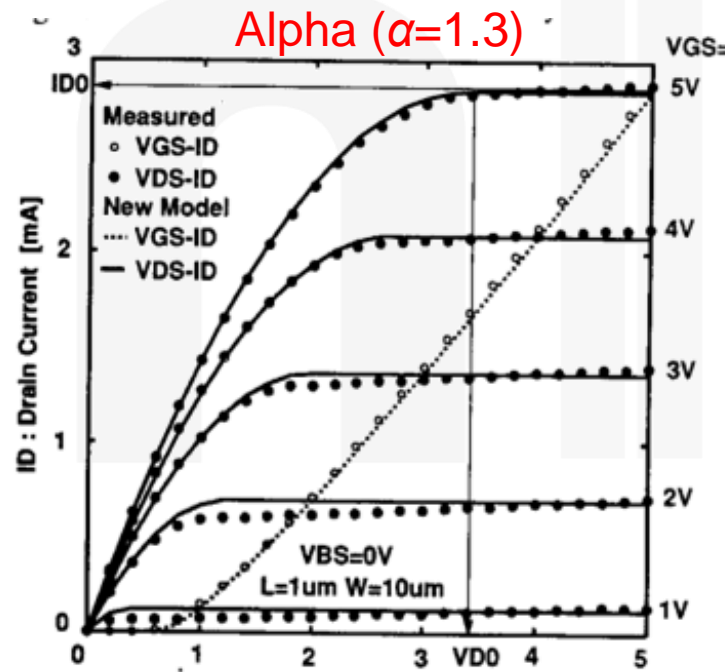
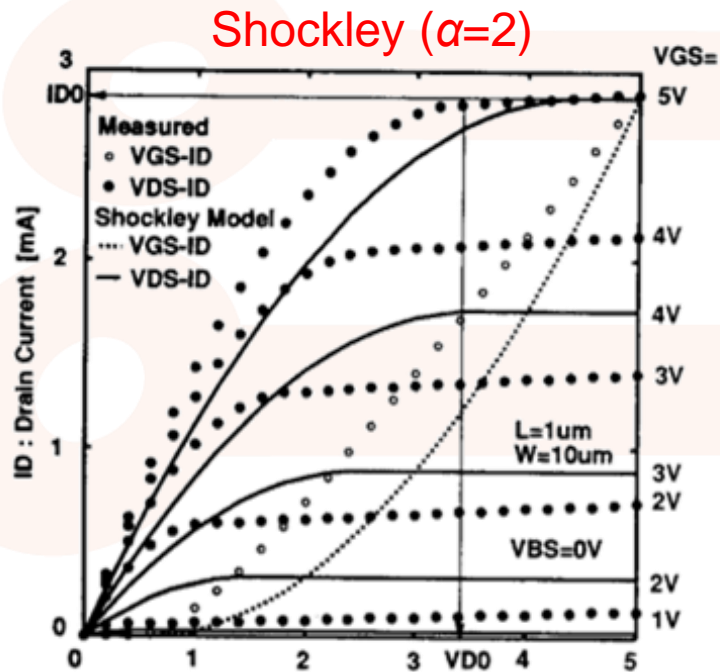
$$I_{DS} = \begin{cases} 0 & V_{GS} < V_T^* \\ k_n (V_{GS} - V_T^*) V_{DSAT} & V_{GS} > V_T^* \end{cases}$$



# The Alpha Power Law Model

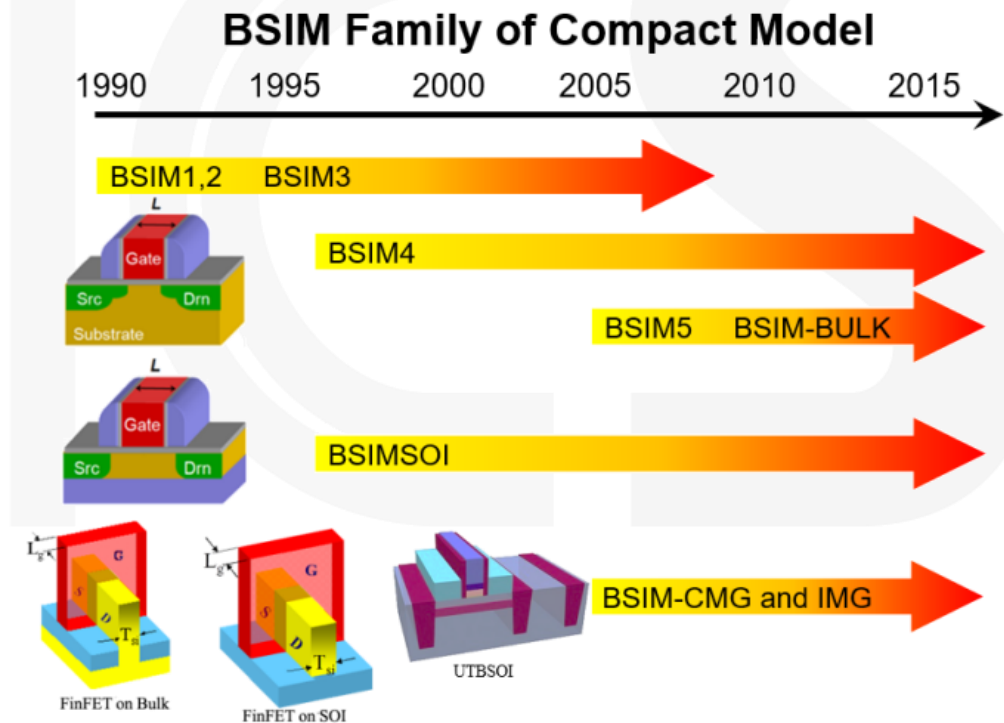
- Sakurai found that by changing the exponent of the square law, a better fit can be found with simple calculations.

$$I_{DSAT}(\alpha) = \mu_n C_{ox} \frac{W}{2L} (V_{GS} - V_T)^\alpha$$

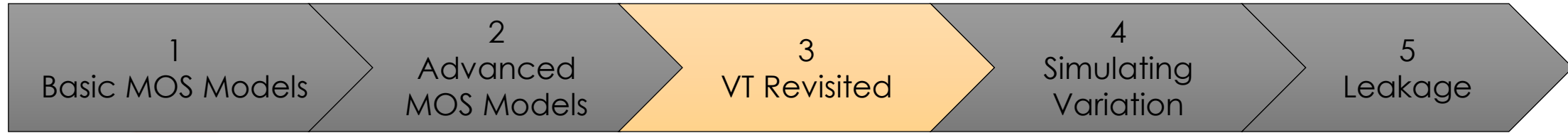


# BSIM and Newer Models

- **BSIM** (Berkeley Short-channel IGFET Model) is the **primary compact model family** used for **SPICE** simulation for the last three decades.
- These model use hundreds of parameters to achieve a good fit.
- **BSIM4** is the main model for bulk CMOS
  - Takes into account most physical effects as well as many fitting parameters.
- **The Compact Model Coalition (CMC)** chooses, maintains and promotes new models
  - Additional models include **EKV**, **PSP**, and models for non-MOS devices.



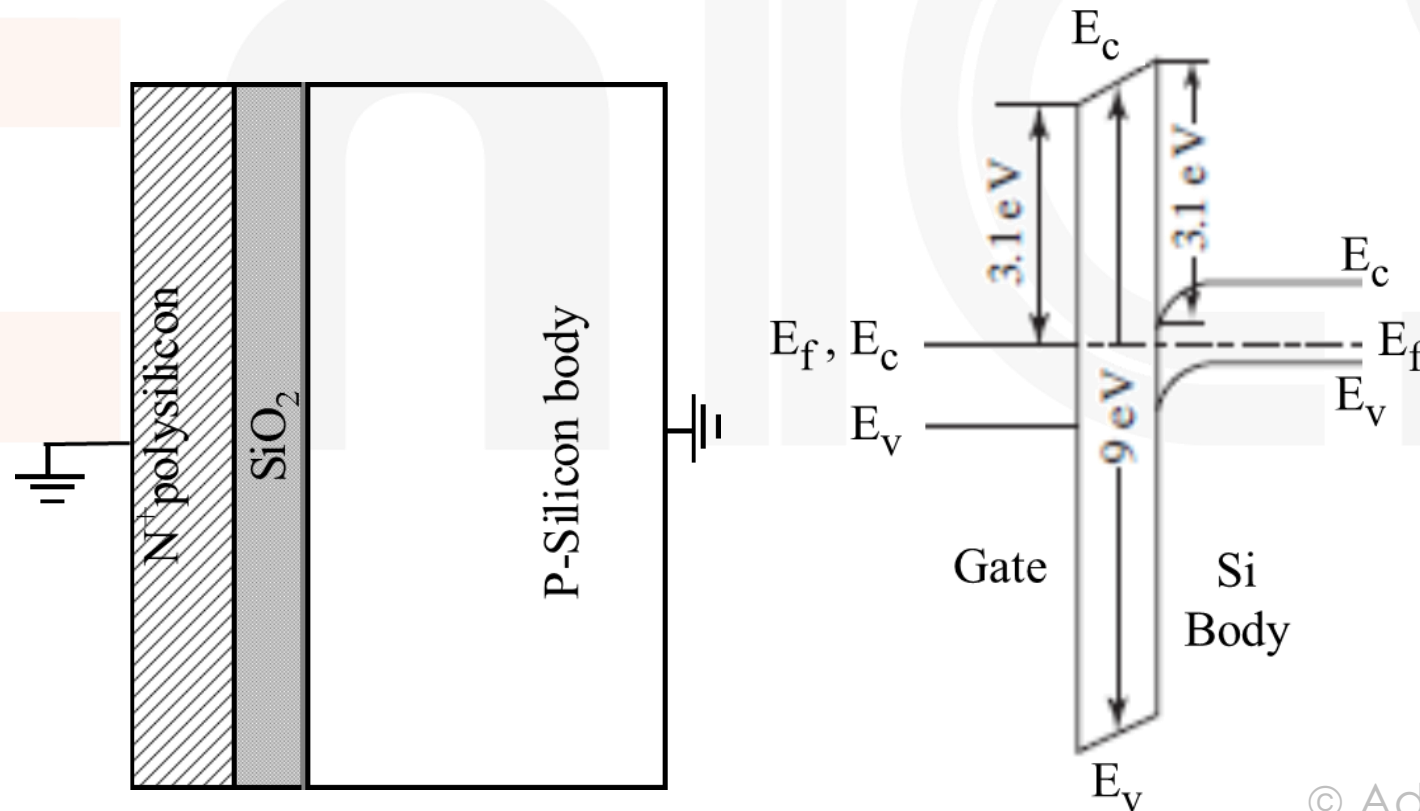
Source: Yen Ki Lin, UC Berkeley



# Threshold Voltage Revisited

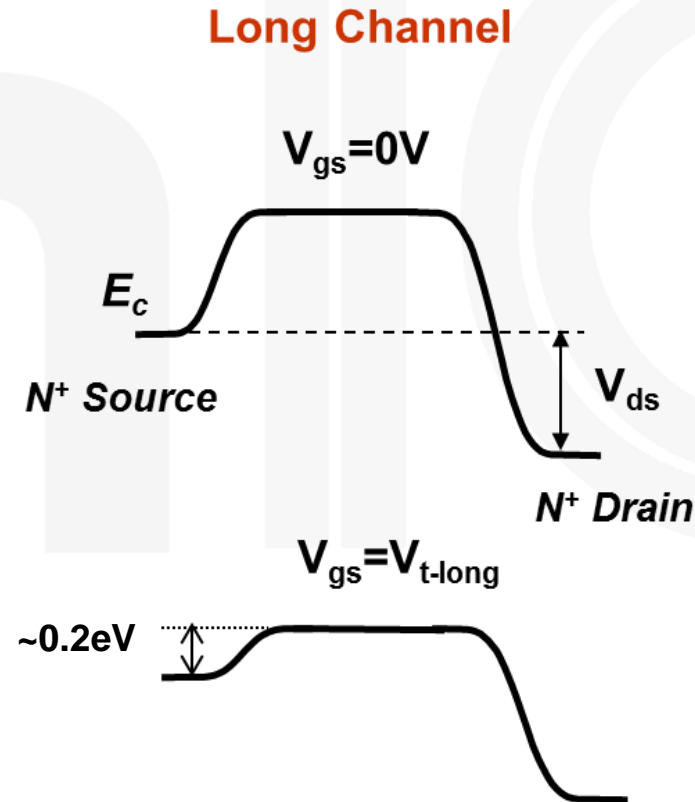
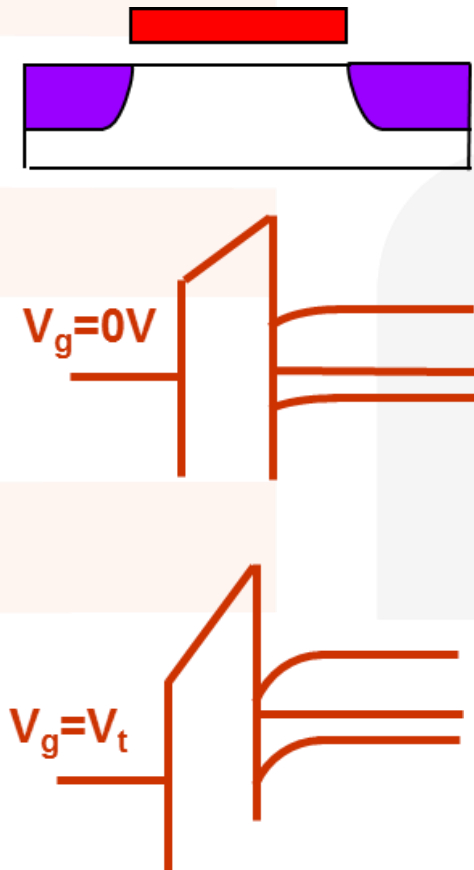
# Energy Band Diagrams

- To understand the **threshold voltage** and other **secondary effects** of the MOS device, we often use **energy band diagrams**.
- The first approach is looking in from the gate:



# Energy Band Diagrams

- The second approach is looking from the source to the drain.



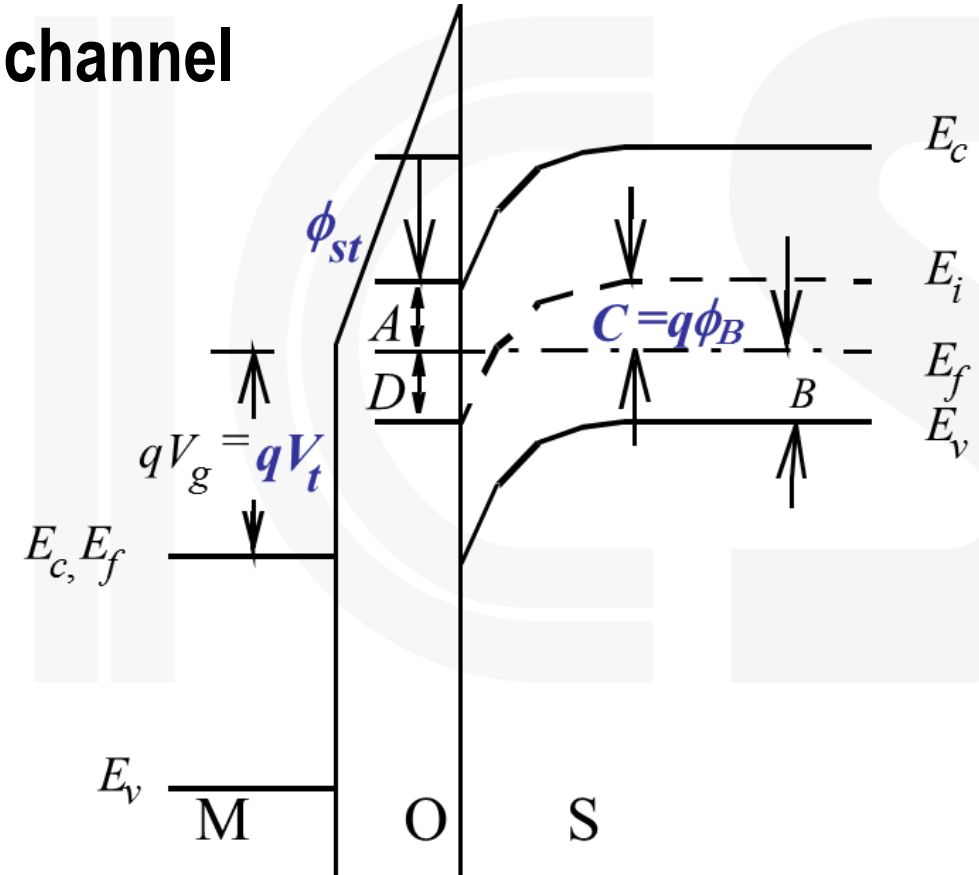
# Threshold Voltage - Basic Theory

- The basic definition of threshold voltage is the **gate voltage** ( $V_G$ ) required to **invert** the channel

$$V_{T0} = \Phi_{MS} - 2\Phi_F - \frac{Q_{OX}}{C_{ox}} - \frac{Q_{dep}}{C_{ox}} - \frac{Q_I}{C_{ox}}$$

$$Q_{dep} = \sqrt{2qN_A\epsilon_{si}|-2\Phi_F|}$$

$$\Phi_F = -\phi_T \ln \frac{N_A}{n_i} \quad \phi_T \equiv \frac{kT}{q}$$



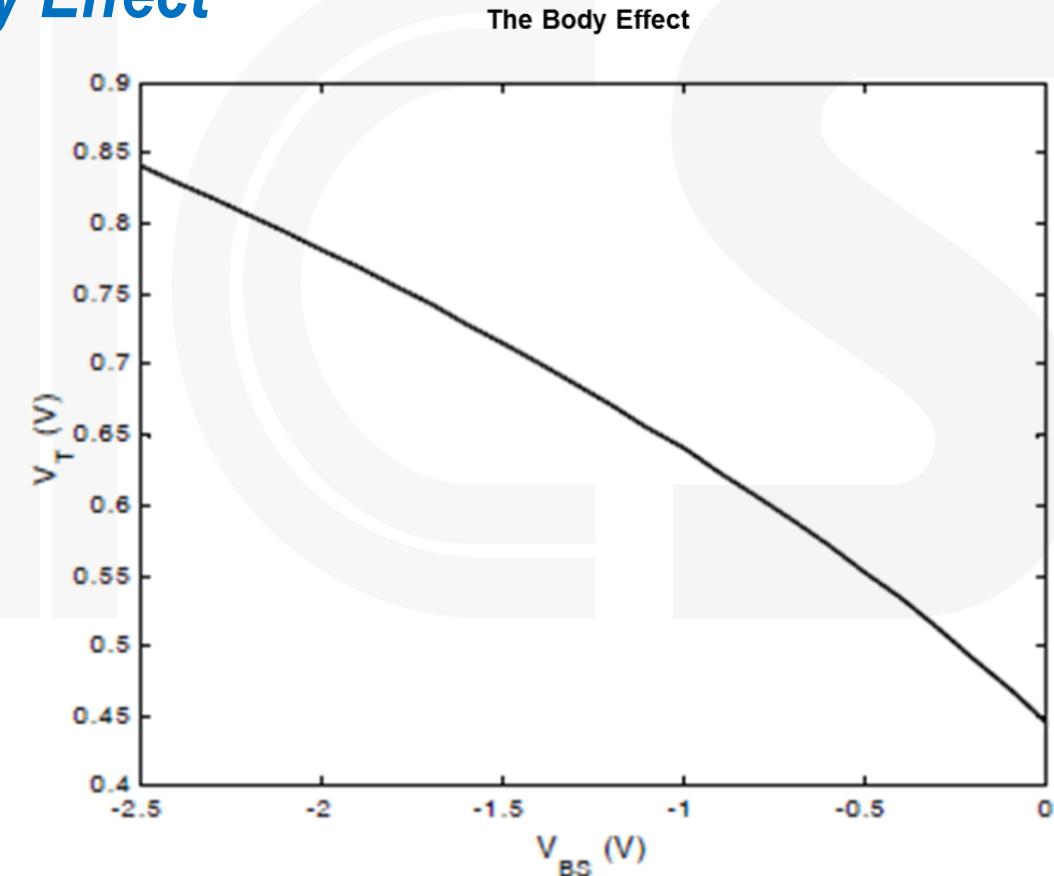
# Body Effect

- The appearance of a voltage difference between the **source** and **body** ( $V_{SB}$ ) is known as “*The Body Effect*”
- This can be modeled by the additional charge that needs to be depleted.

$$Q_{dep} = \sqrt{2qN_A\epsilon_{si} \left( |-2\Phi_F + V_{SB}| \right)}$$

$$V_T = V_{T0} + \gamma \left( \sqrt{|-2\Phi_F + V_{SB}|} - \sqrt{|-2\Phi_F|} \right)$$

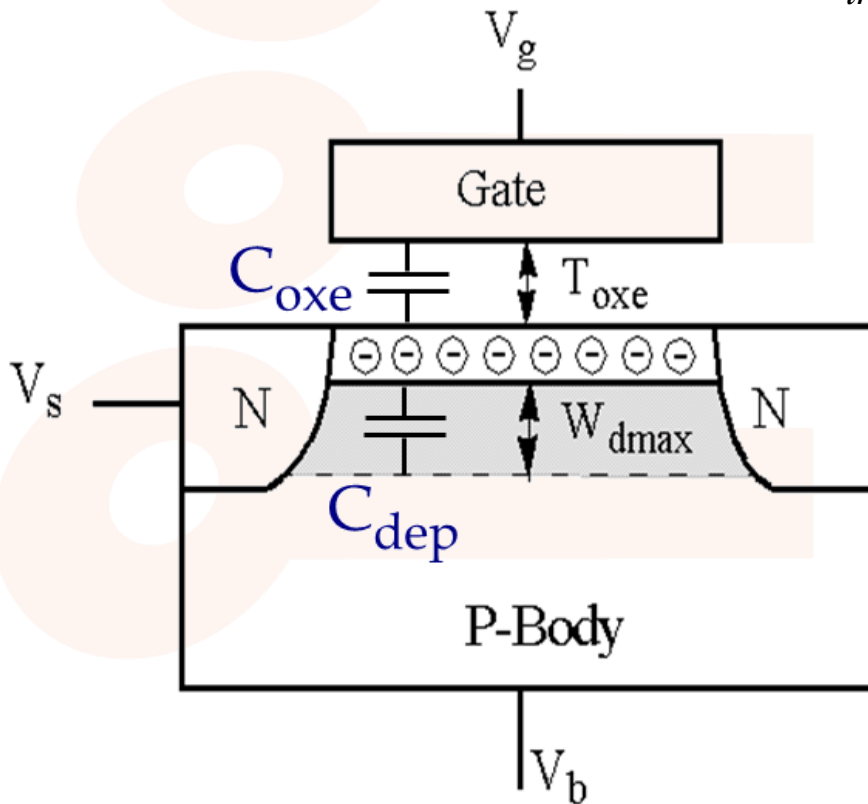
$$V_{T0} \equiv \Phi_{MS} - 2\Phi_F - \frac{Q_{ox}}{C_{ox}} - \frac{Q_{dep0}}{C_{ox}} \quad \gamma = \frac{\sqrt{2q\epsilon_{si}N_A}}{C_{ox}}$$





# Modern Body Effect

- A different approach is to look at the capacitive voltage divider between the **gate** and **body** ( $C_{GB}$ )

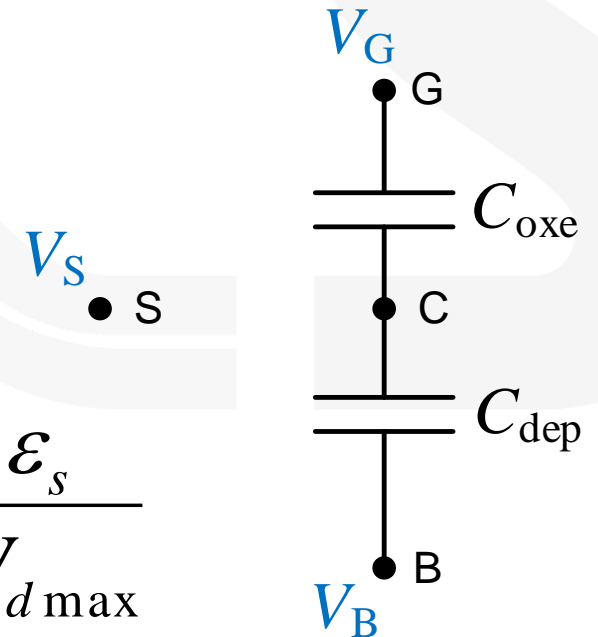


$$Q_{inv} = -C_{oxe} (V_{GS} - V_{CS} - V_{T0}) + C_{dep} (V_{SB} + V_{CS})$$

$$= -C_{oxe} (V_{GS} - nV_{CS} - V_{T0})$$

$$n \triangleq 1 + \frac{C_{dep}}{C_{oxe}} = 1 + \frac{3T_{oxe}}{W_{dmax}}$$

$$C_{dep} = \frac{\epsilon_s}{W_{dmax}}$$



# Modern Body Effect

- This can be shown to **redefine**  $V_T$  as:

$$V_T(V_{SB}) = V_{T0} + \frac{C_{dep}}{C_{oxe}} V_{SB}$$

- In modern technologies,  $C_{dep}/C_{oxe}$  is a constant, so  $V_T$  is **linearly dependent** on  $V_{SB}$ !

# Poly Depletion and Channel Depth

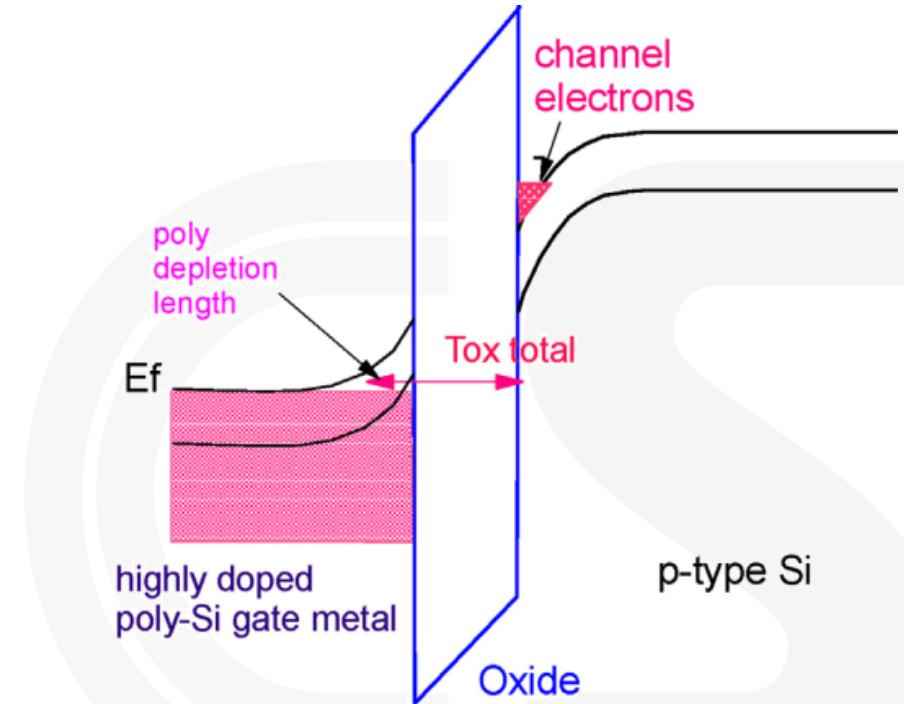
The threshold voltage is affected by two additional factors that we have disregarded until now:

- **Polysilicon Depletion**

- Since polysilicon is, itself, a semiconductor, the depletion layer into the poly effectively increases the oxide thickness.

- **Channel Depth**

- Since the channel is not a 2-dimensional line along the surface, the oxide thickness is essentially increased.



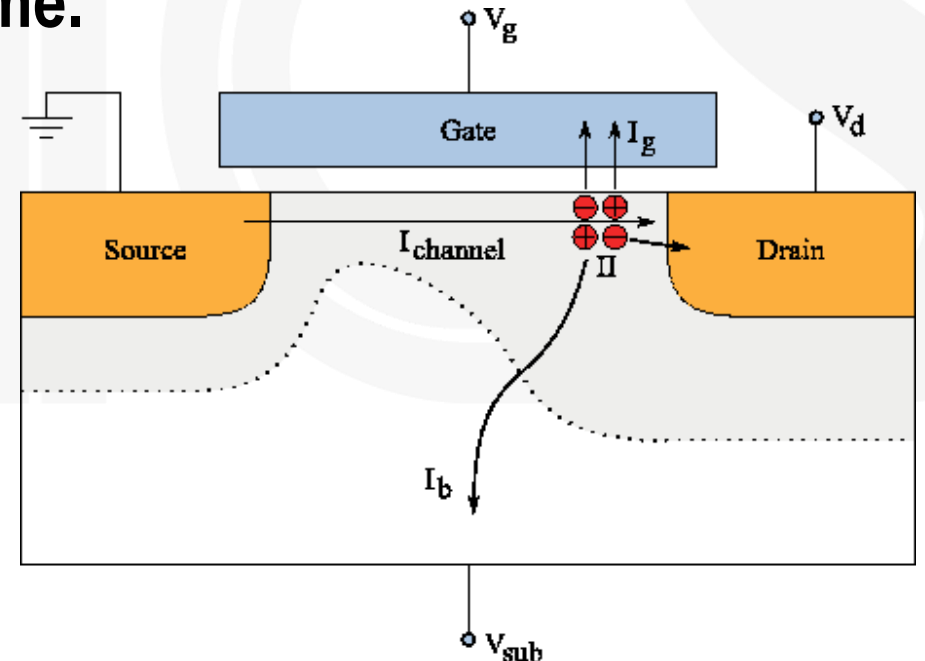
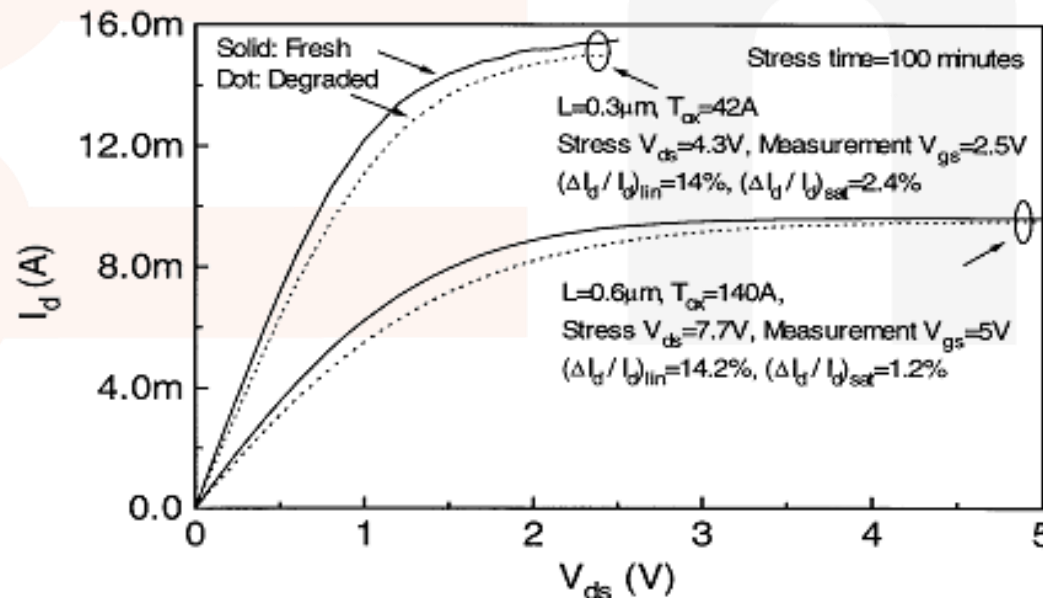
$$n \triangleq 1 + \frac{C_{dep}}{C_{oxe}} = 1 + \frac{3T_{oxe}}{W_{d\max}}$$

# Hot Carrier Effects

- Electrons can get so *fast* that they can **tunnel into the gate oxide** and **increase the threshold voltage**.

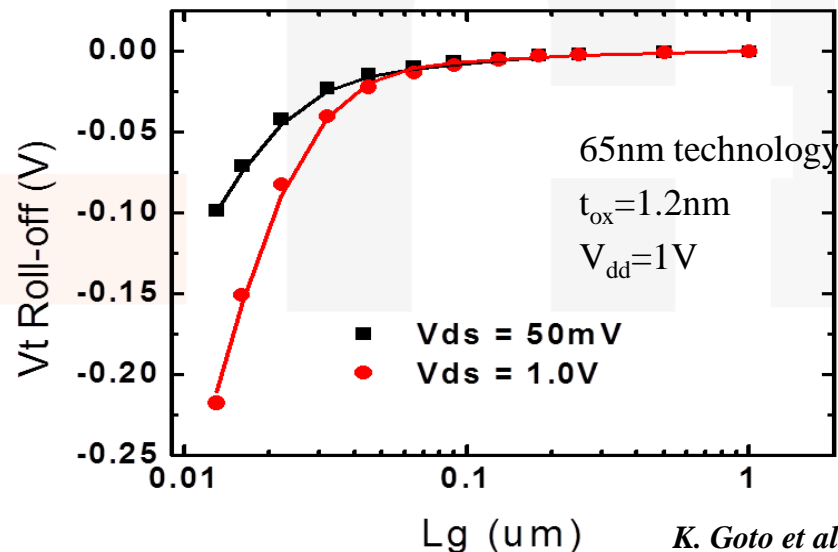
$$V_{T0} = \Phi_{MS} - 2\Phi_F - \frac{Q_{OX}}{C_{ox}} - \frac{Q_{dep}}{C_{ox}} - \frac{Q_I}{C_{ox}}$$

- This is a reliability issue as it happens over time.

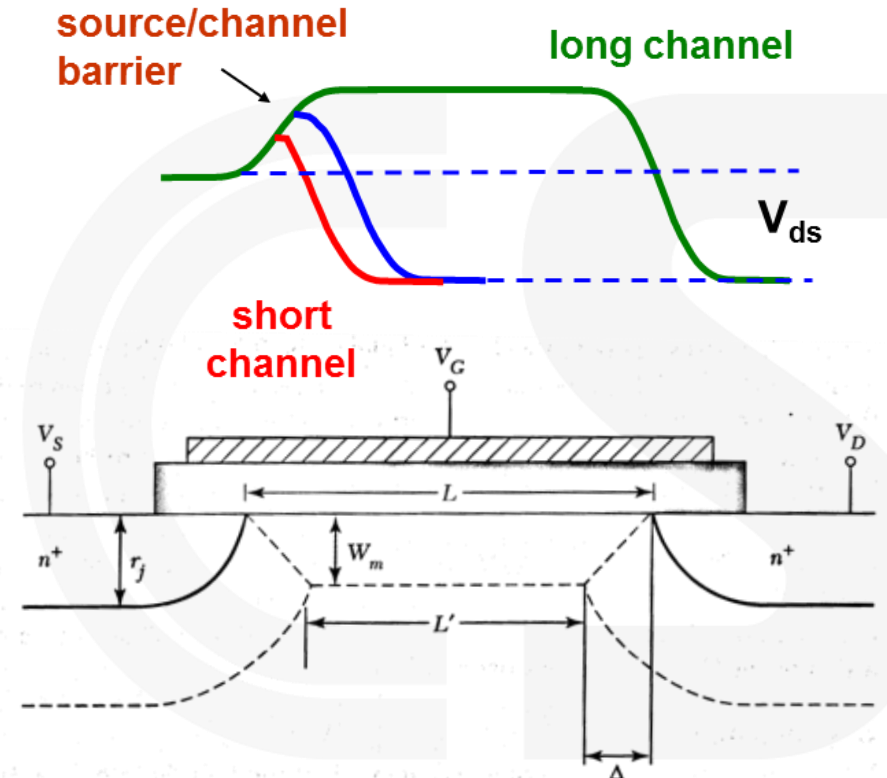


# $V_T$ Roll Off (Short Channel Effect)

- As **channel length** is reduced, **effective channel length is reduced** by depletion regions.
- A trapezoid is created under the gate, dividing the channel into the region controlled by the gates and by the drain.
- In essence,  **$V_T$  is reduced.**

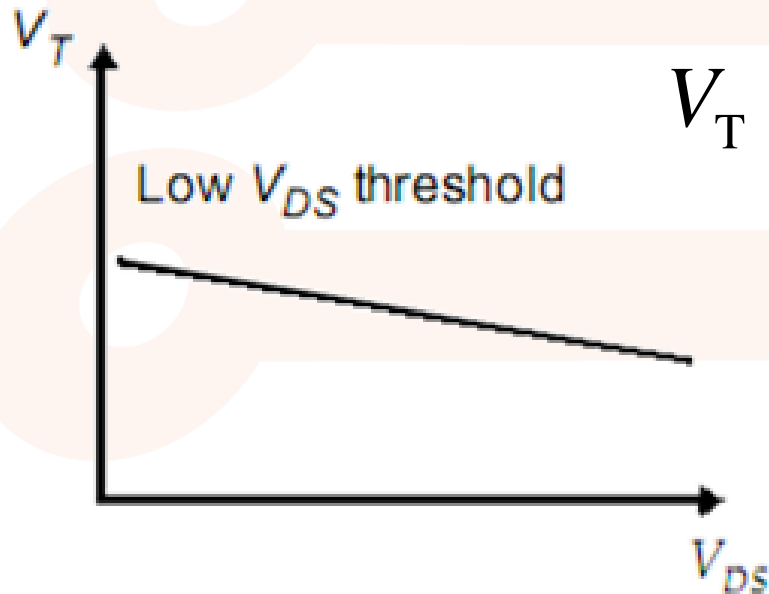


K. Goto et al., IEDM 2003

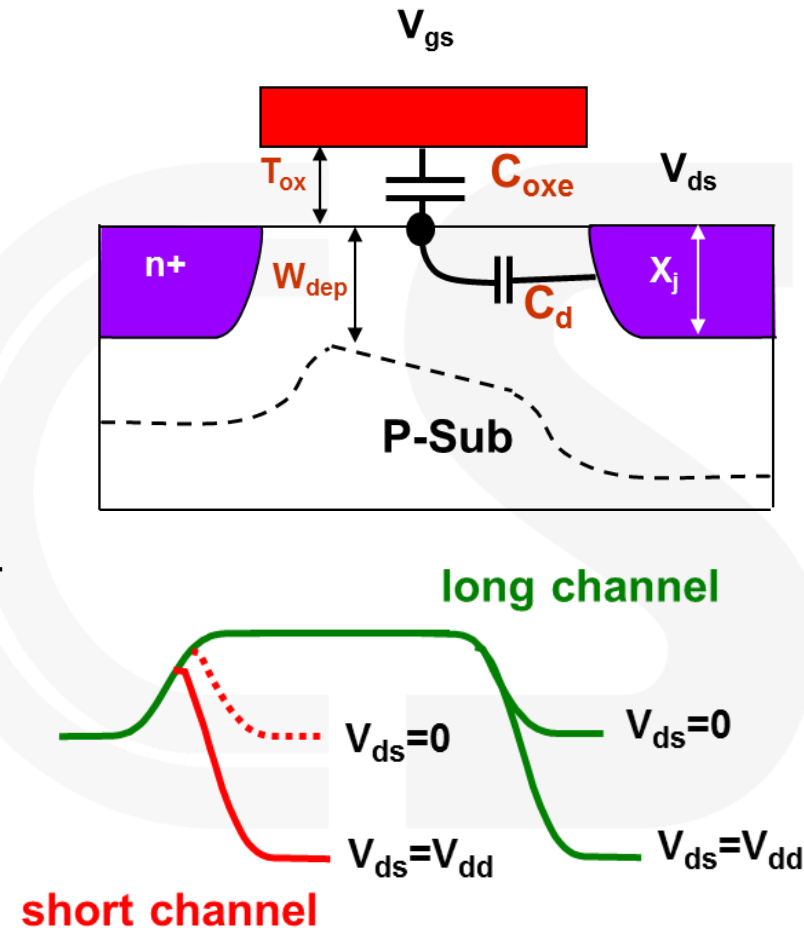


# DIBL (Drain Induced Barrier Lowering)

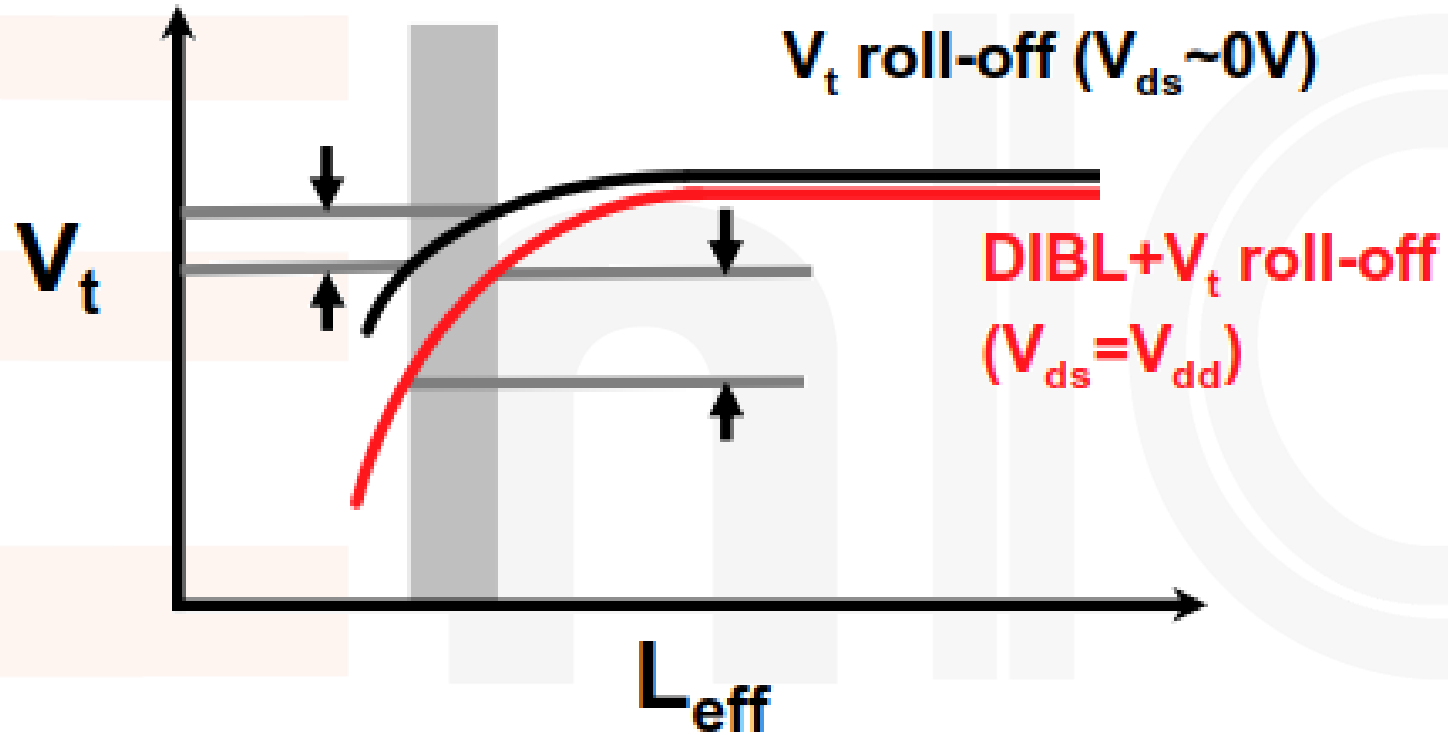
- In short channels, the barrier of the channel is essentially lowered, as the drain causes the energy band to drop closer to the source.
- This is exponentially dependent on  $V_{DS}$ .



$$V_T = V_{T, \text{long}} - (V_{DS} + 0.4) \cdot \frac{C_d}{C_{\text{oxe}}}$$



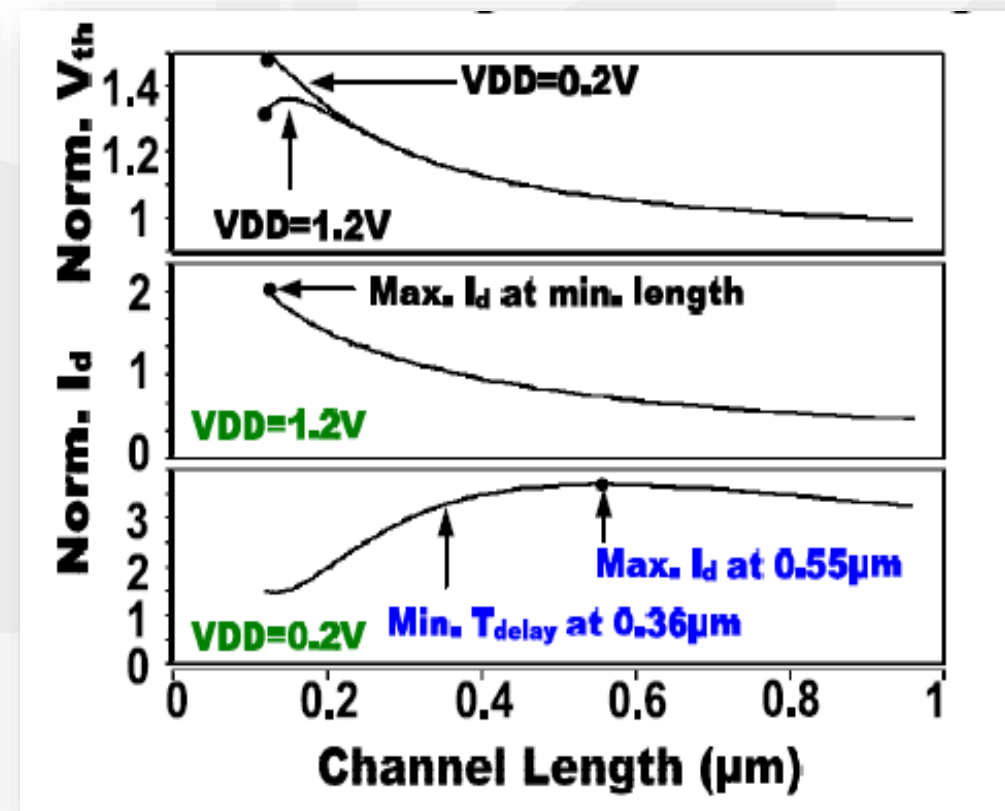
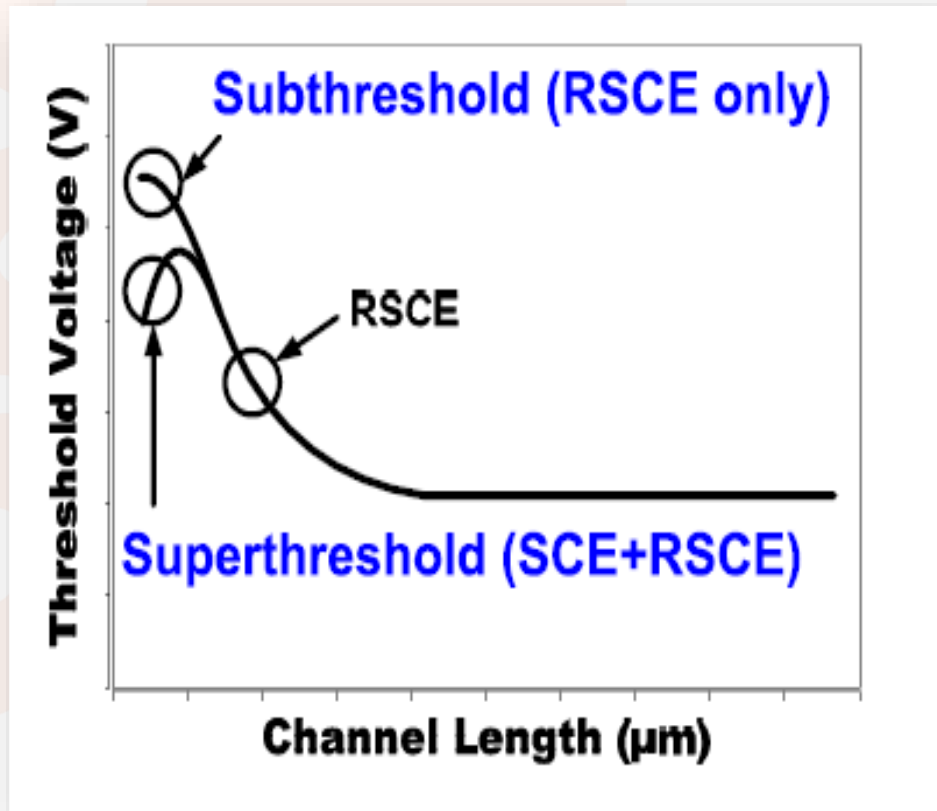
# Roll Off / DIBL combined



Source: Chris Kim, U. Minn

# Reverse Short Channel Effect (RSCE)

- $V_T$  actually *increases* at channel lengths a bit higher than minimum...



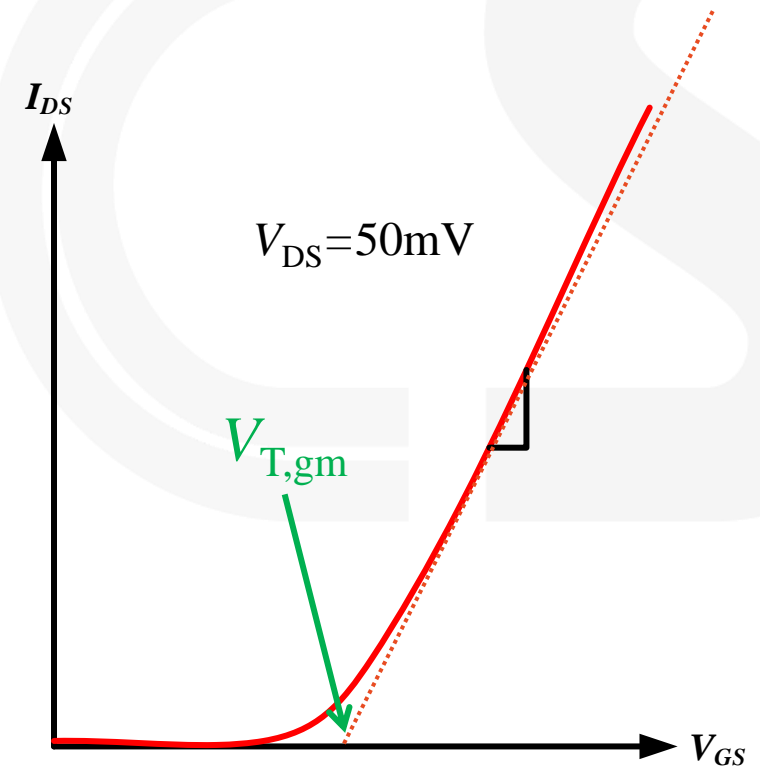


# How to Measure $V_T$

- There are various ways to measure  $V_T$
- One classic way takes a small  $V_{DS}$  and sweeps  $V_{GS}$ .

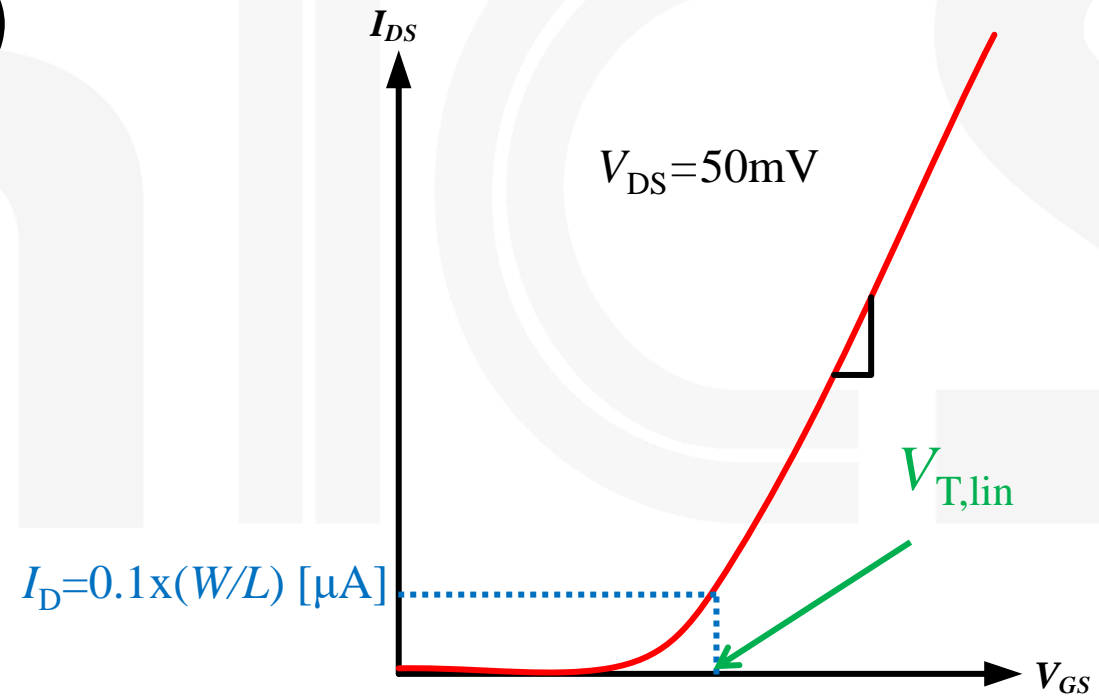
$$I_d = k \left[ (V_{GS} - V_T) V_{DS} - 0.5 V_{DS}^2 \right] \propto V_{GS} - V_T$$

- So we can find the  $V_{GS}$  at which the linear part crosses  $I_{ds}=0$ .



# How to Measure $V_T$

- One of the more common ways is to find the  $V_{GS}$  at which  $I_{DS}=100 \text{ nA} \times W/L$ .
- For  $V_{T,lin}$ , set a low  $V_{DS}$  ( $V_{DS}=50\text{mV}$ )
- For  $V_{T,sat}$  set a high  $V_{DS}$  ( $V_{DS}=V_{DD}$ )



# Note about Simulation

- The first step of all Spice (Spectre) simulations is a DC Operating Point calculation.



# Simulation tip: OP and MP in Spectre

- So we saw that the threshold voltage is dependent on the operating point.
- How do you know what the  $V_T$  of a transistor is in a given simulation?
- To find  $V_{T0}$ , use the “**MP**” option.
- To find  $V_{T,lin}$ ,  $V_{T,sat}$ ,  $V_{T,gm}$ , use the “**OP**” option.
- How would you go about plotting roll-off (SCE) and RSCE?

# The Computer Hall of Fame

- We generally consider the ENIAC to be the first computer, but the official first fully electronic computer was the

## ACE

- *Atansoff-Berry Computer*

Conceived in 1937, operational in 1942

- Built at Iowa State University by Prof. John Atansoff and his student Clifford Berry.
- Not programmable nor Turing-complete, but included binary arithmetic and electronic switching elements.
- A patent dispute over the first electronic computer was settled in 1973, when the patent of the ENIAC was invalidated.



Source: wikipedia



Source: wikipedia

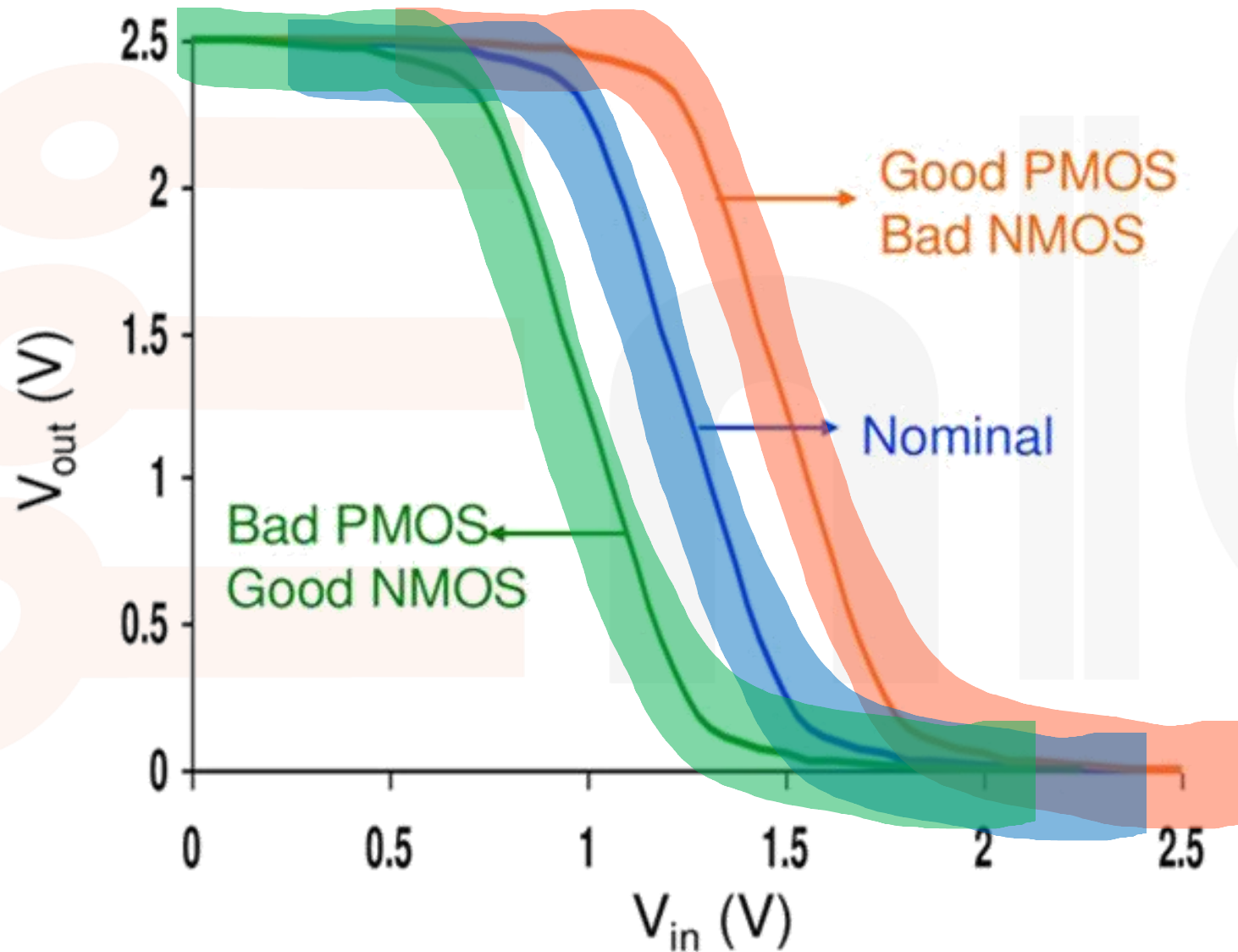


# Simulating Variation

Process Corners and Monte Carlo Simulation



# Reminder: Impact of Process Variations



*How do we take this into consideration during simulation?*

# Remove the Rust: Probability Basics

- **Properties of Random Variables**

- The **probability distribution function (PDF)**  $f(x)$  specifies the probability that a value of a continuous random variable  $X$  falls in a particular interval:

$$P[a < X \leq b] = \int_a^b f(x) dx$$

- The **cumulative distribution function (CDF)**  $F(x)$  specifies the probability that  $X$  is less than some value  $x$ :

$$F(x) = P[X < x] = \int_{-\infty}^x f(u) du \qquad f(x) = \frac{d}{dx} F(x)$$

- The **mean** ( $\mu$ ) and **variance** ( $\sigma^2$ ) are defined as:

$$\mu(X) = \bar{X} = E[X] = \int_{-\infty}^{\infty} x \cdot f(x) dx \qquad \sigma^2(X) = E\left[(x - \bar{X})^2\right] = \int_{-\infty}^{\infty} (x - \bar{X})^2 f(x) dx$$



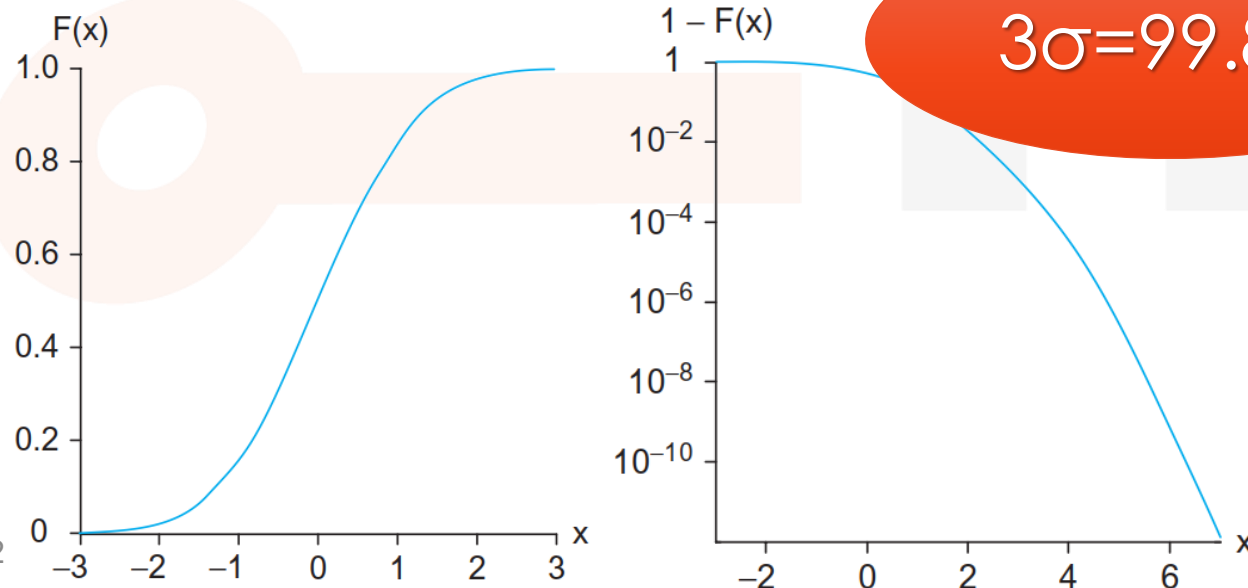
# Remove the Rust: Probability Basics

- **Normal Random Variables**

- A normal (Gaussian) random variable, shifted to have a zero mean ( $\mu=0$ ) and a normalized standard variation ( $\sigma^2=1$ ) has:

$$f(x) = \frac{1}{\sqrt{2\pi}} e^{-\frac{1}{2}x^2}$$

$$F(x) = \frac{1}{2} \left[ 1 + \operatorname{erf} \left( \frac{x}{\sqrt{2}} \right) \right]$$

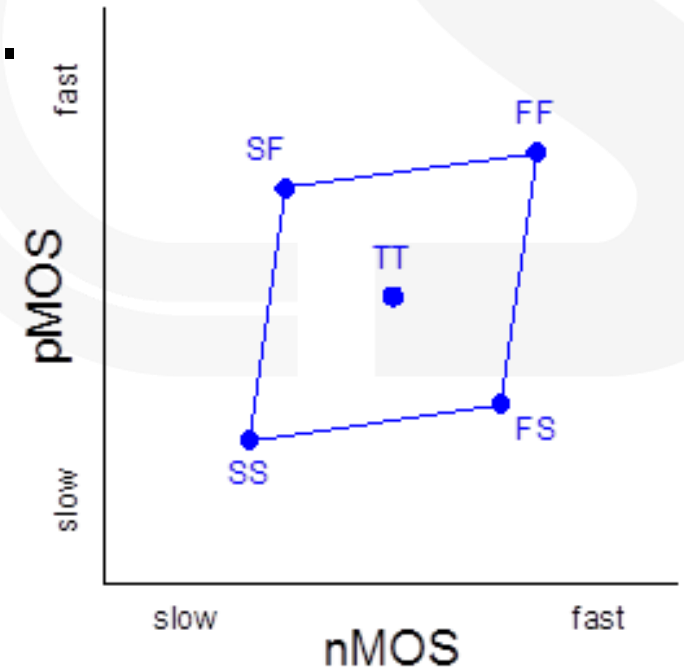


	$F(x)$	$1 - F(x)$
2	0.8413	$1.59 \times 10^{-1}$
3	0.9772	$2.28 \times 10^{-2}$
4	0.998650	$1.35 \times 10^{-3}$
5	0.9999683	$3.17 \times 10^{-5}$
6	0.999999713	$2.87 \times 10^{-7}$
7	0.99999999013	$9.87 \times 10^{-10}$

$6\sigma =$   
1 in a billion











# Global Variation Modeling: Process Corners

- **Global Variation assumption:**
  - If a certain process step is *skewed*, the entire chip is affected equivalently.
  - We will define “*corner cases*” of fabrication, i.e.,  $3\sigma$  from the mean.
  - We also assume the **voltage** and **temperature** are globally affected.
- **Devices are modeled for *fast*, *slow* and *nominal* corners.**
  - Changes in  $V_T$ ,  $W$ ,  $L$ ,  $t_{ox}$
- **Devices are tested at various *temperatures***
  - Temperature affects **mobility** and  $V_T$ .
  - Typically  $0^\circ\text{C} - 85^\circ\text{C}$  or  $-40^\circ\text{C} - 125^\circ\text{C}$
- **Devices are tested at various supply voltages**
  - Higher voltages cause increased currents
  - Typically  $\pm 10\% V_{DD}$



# Process Corners

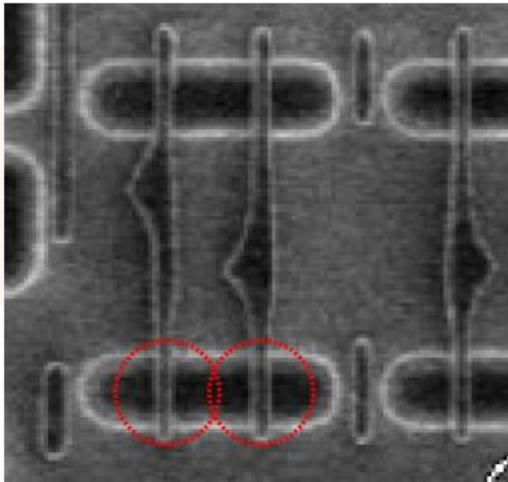
- What are the **PVT** (=Process, Voltage, Temperature) settings for each simulation corner?

Corner	$V_T$	$L_{eff}$	$t_{ox}$	$V_{DD}$	$T$
Fast					
Typical	X	X	X	X	X
Slow					

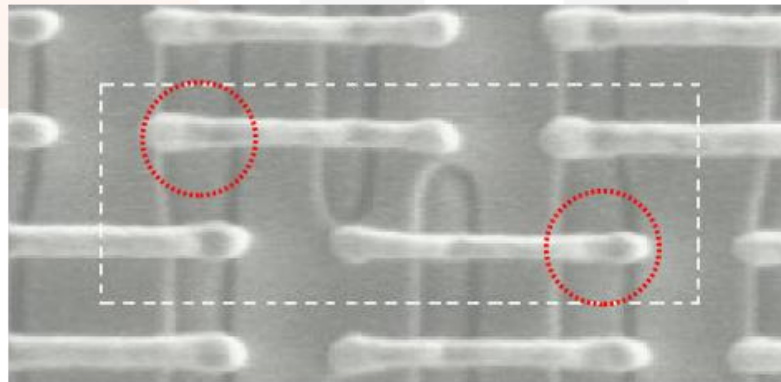
# What about Local Variation?

- Often there are *too many* parameters to think about and setting a specific corner case is insufficient.
- For example: **Pelgrom's Law**
  - $V_T$  **variance** is inversely proportional to transistor area

$$\sigma(V_T) = \frac{K}{\sqrt{W \cdot L}}$$

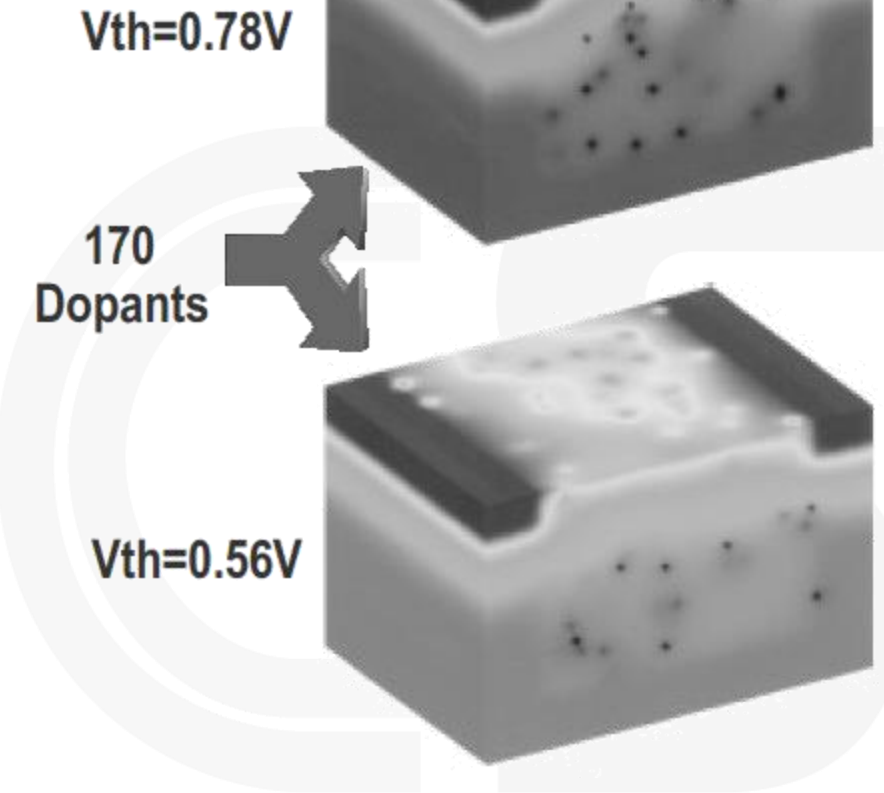


65nm CMOS NAND cell



Intel 65nm 6T SRAM cell

Source: Stanford, EE380

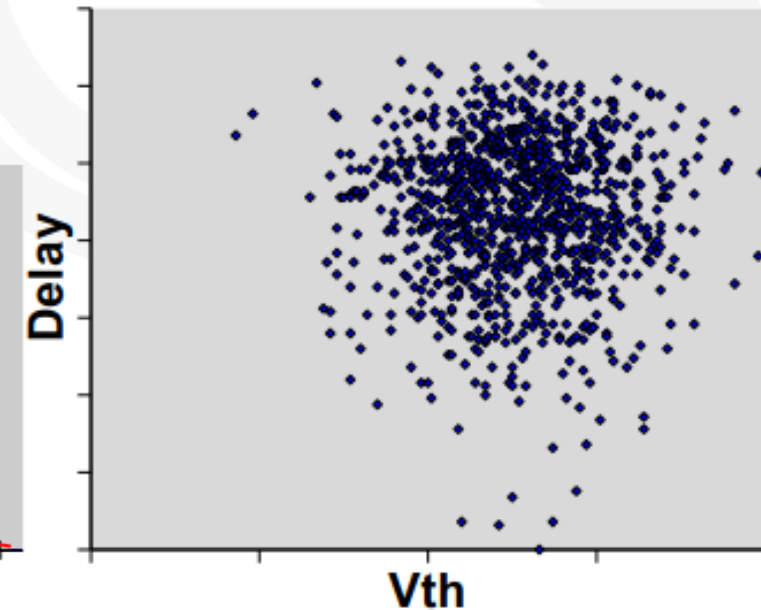
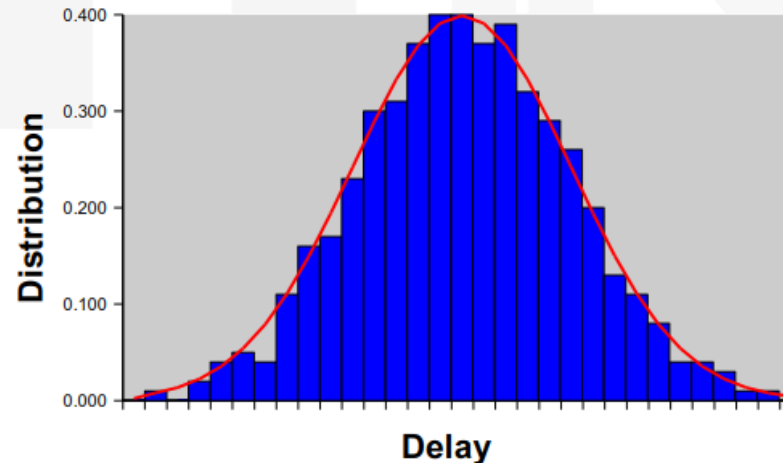
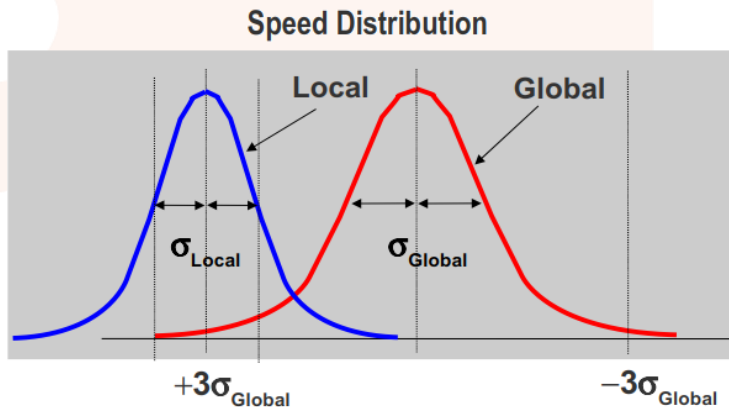
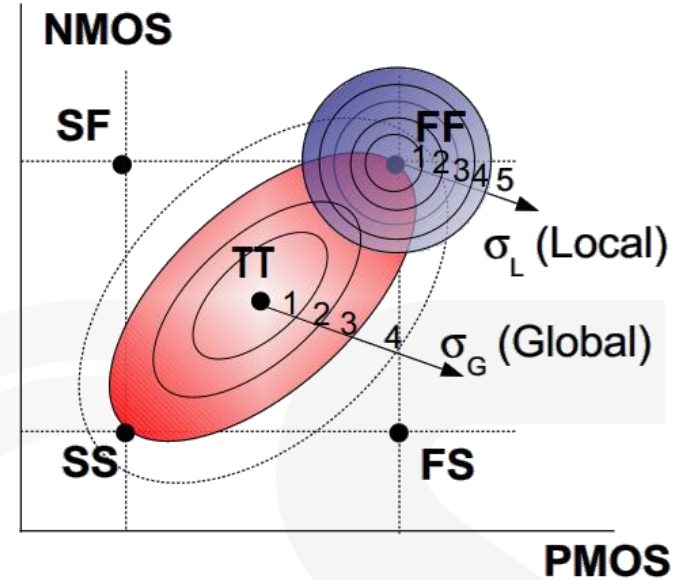


Source: Asenov, IEEE TED 1998

*How do we deal with this?*

# Monte Carlo Simulation

- The basic approach is to “roll the dice” for each parameter and run a simulation.
  - These are called **Monte Carlo** Statistical Simulations.
- The result is a distribution plot of design constraints, e.g., delay or noise margin
- Both **Global** and **Local Variations** can be taken into consideration.



# Simulation questions

- How do we plot threshold voltage variation?

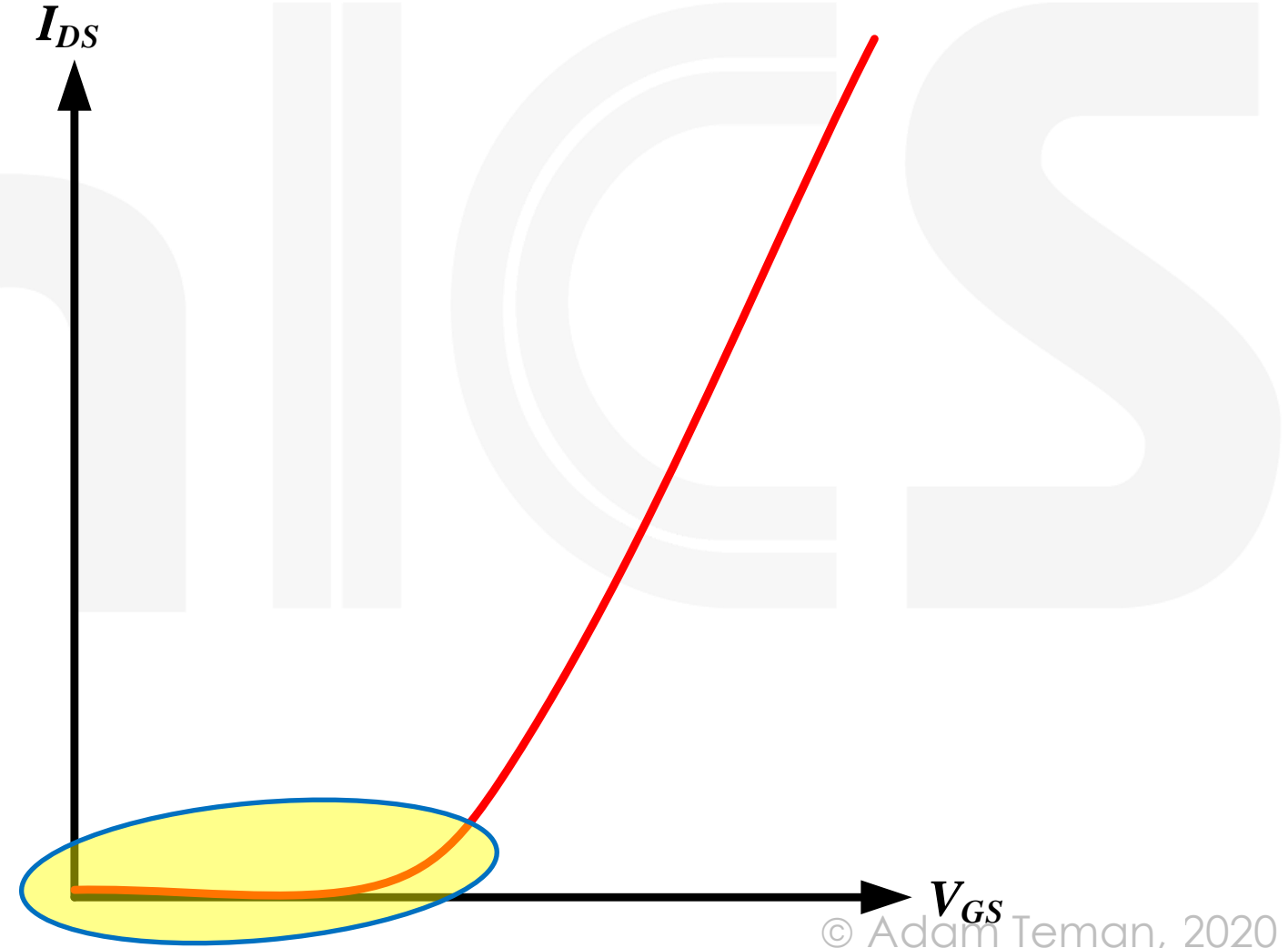
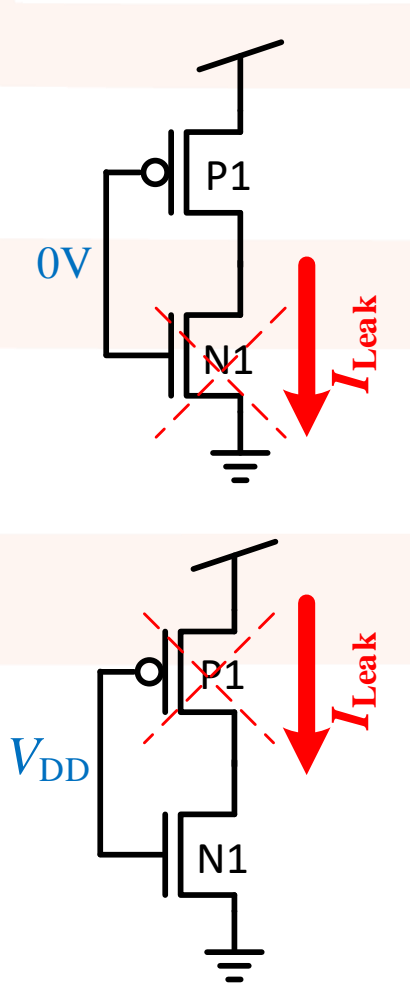




# Leakage in NanoScaled Transistors

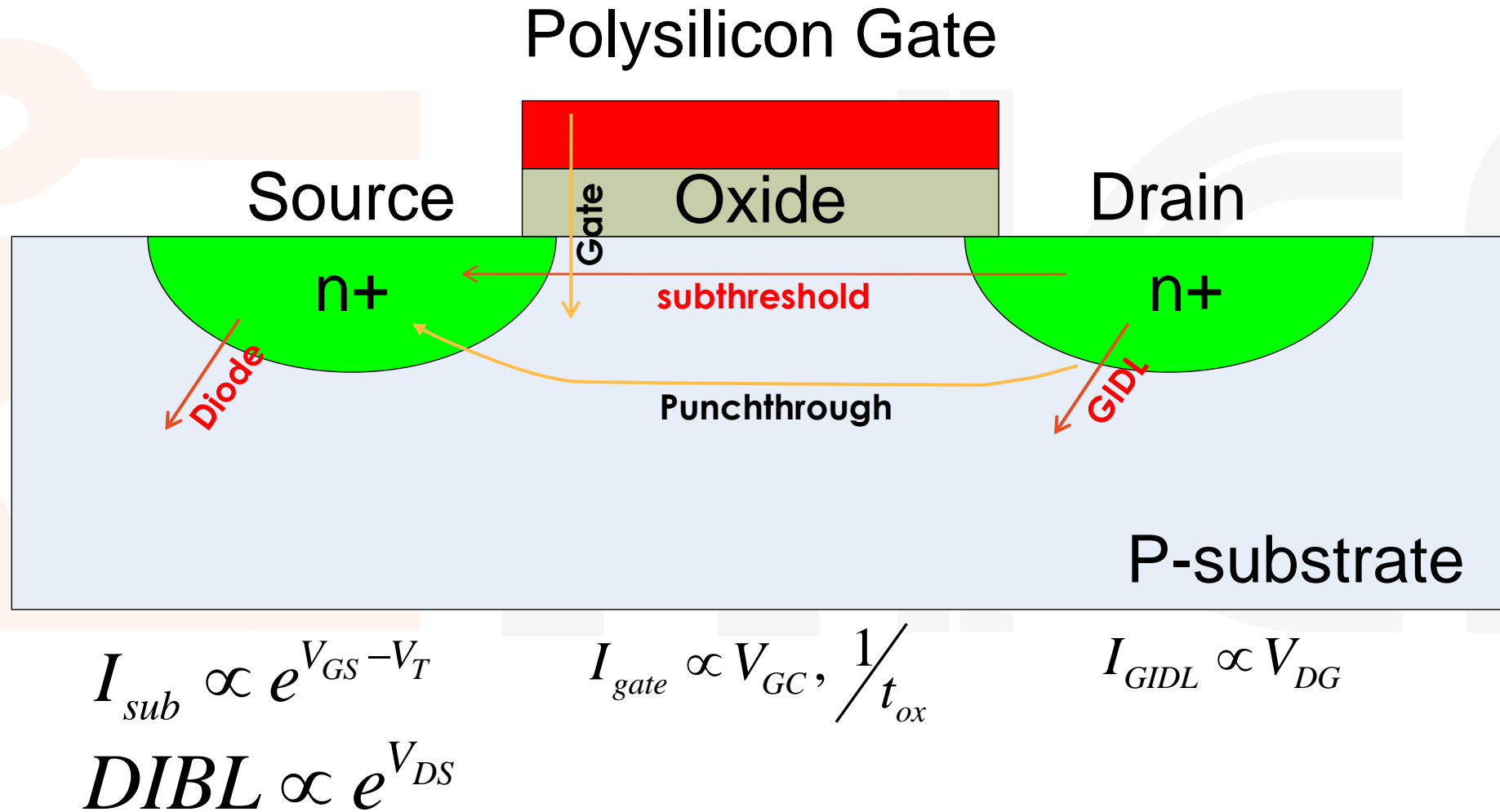
# Leakage in Nanoscaled Transistors

- Transistors that are supposed to be off actually leak!





# Main Types of Leakage

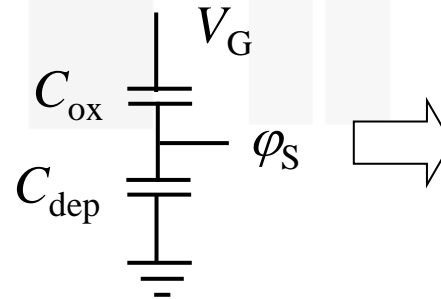
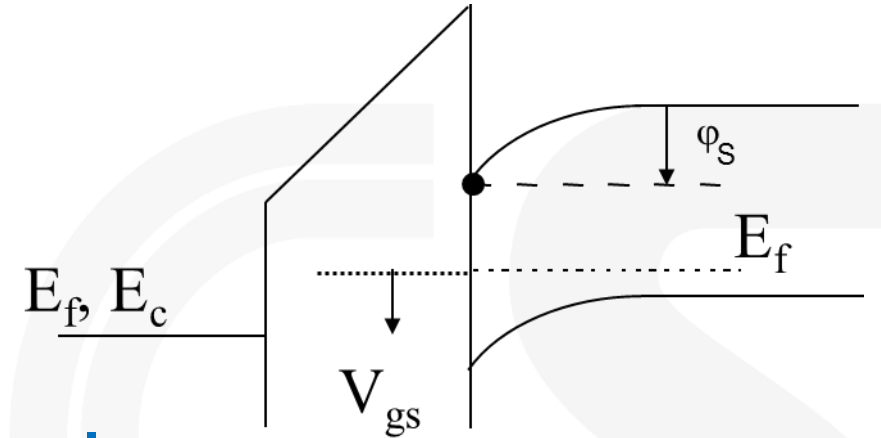


# Subthreshold Leakage

- When  $V_{GS} < V_T$ , there is still a **finite carrier concentration** at the surface:

$$n_s \propto e^{\varphi_s / \phi_T} \Rightarrow I_{sub} \propto e^{(V_{GS} - V_T) / n\phi_T}$$

- As we saw with the body effect, due to **bulk to channel capacitance**, the surface voltage **isn't only controlled by the gate**:



$$n \equiv 1 + \frac{C_{dep}}{C_{oxe}}$$

$$\frac{d\varphi_s}{dV_G} = \frac{C_{oxe}}{C_{oxe} + C_{dep}} = \frac{1}{n}$$

# Subthreshold Leakage

- Let's make things easier:

- Remember that:

$$I_{DS}(\text{sub}) = \text{Const} \frac{W}{L} \cdot e^{\frac{V_{GS} - V_T}{n\phi_T}}$$

- And we now defined the **threshold voltage** according to **current**:

$$I_{DS}(V_{GS} = V_T) = 100\text{nA} \cdot \frac{W}{L}$$

- So the **boundary condition** requires:

$$I_{DS}(\text{sub}) \Big|_{V_{GS} = V_T} = \text{Const} \frac{W}{L} \cdot e^{\frac{0}{n\phi_T}} = \text{Const} \frac{W}{L} = 100\text{nA} \frac{W}{L}$$

- And we can now calculate **subthreshold current** as:

$$I_{\text{sub}} [nA] = 100 \frac{W}{L} e^{\frac{V_{GS} - V_T}{n\phi_T}}$$

# Subthreshold Leakage

- An even easier way is to look at the plot of  $\log(I_{DS})=f(V_{GS})$ :

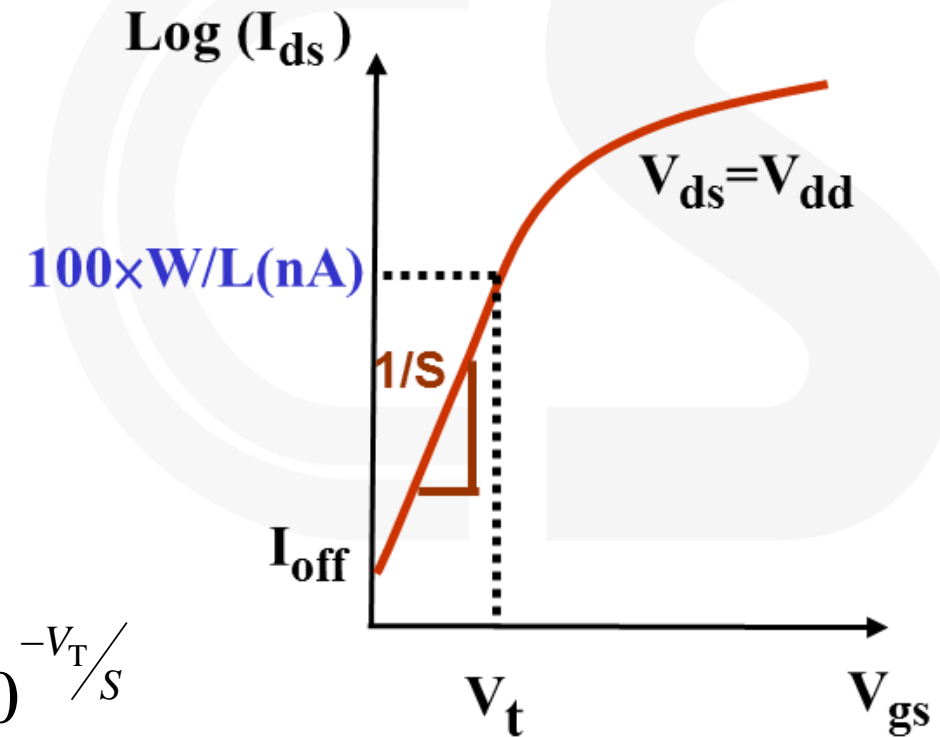
- The slope of this curve is called the “Subthreshold Slope”
- The **inverse** of this slope is known as the “Subthreshold Swing” ( $S$ ):

$$S \equiv \ln(10) \frac{kT}{q} \left( 1 + \frac{C_{dep}}{C_{ox}} \right) = 2.3 \cdot n \cdot \phi_T$$

$$I_{sub} [nA] = 100 \frac{W}{L} e^{\frac{V_{GS}-V_T}{n\phi_T}} = 100 \frac{W}{L} 10^{\frac{V_{GS}-V_T}{S}}$$

- And  $I_{off}$ , which is defined as the current when  $V_{GS}=0$  is:

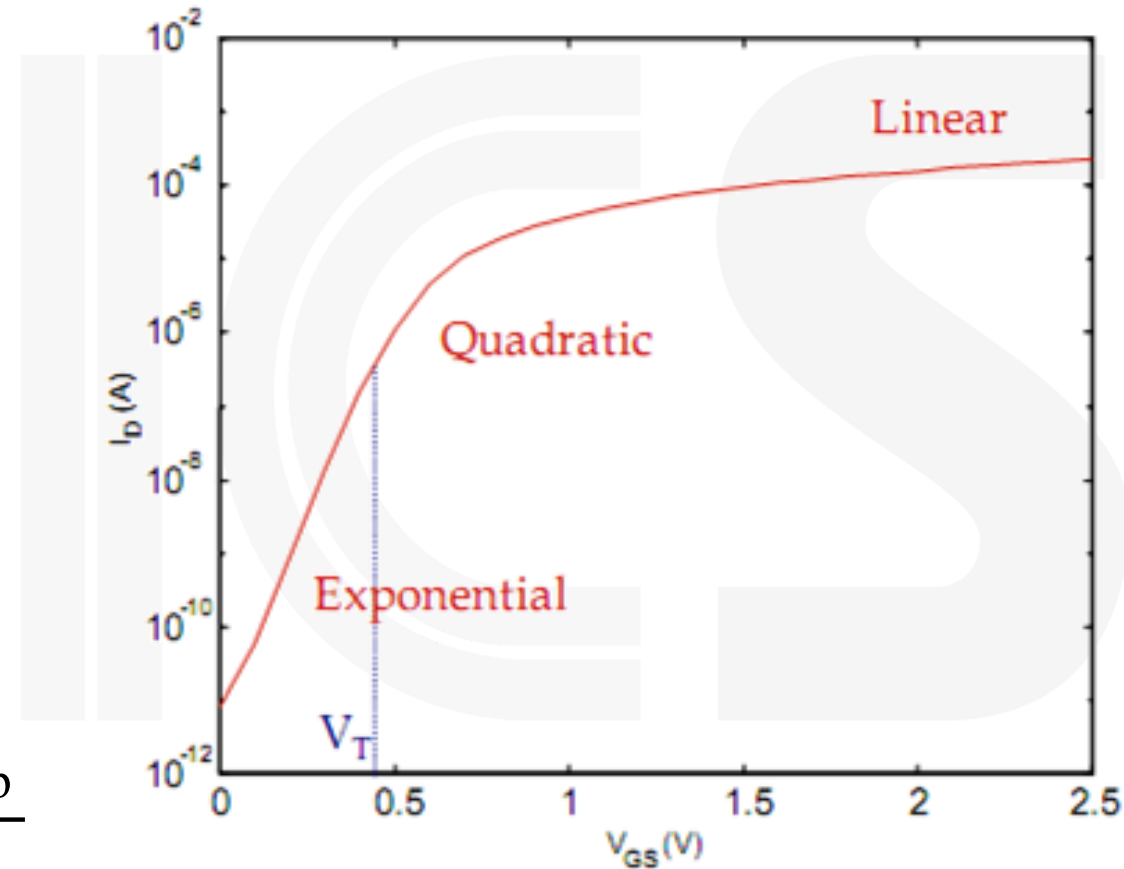
$$I_{off} [nA] = 100 \frac{W}{L} 10^{-\frac{V_T}{S}}$$



# Subthreshold Leakage

- So subthreshold leakage is:
  - Exponentially dependent on  $V_{GS}$ .
  - Exponentially dependent on  $V_T$ .
- $S$  is the subthreshold swing coefficient.
  - Optimally,  $S_{opt}=60$  mV/dec
  - Realistically  $S \approx 100$  mV/dec

$$S \equiv n\phi_T \ln 10 \geq 0.06 \quad n \equiv 1 + \frac{C_{dep}}{C_{oxe}}$$



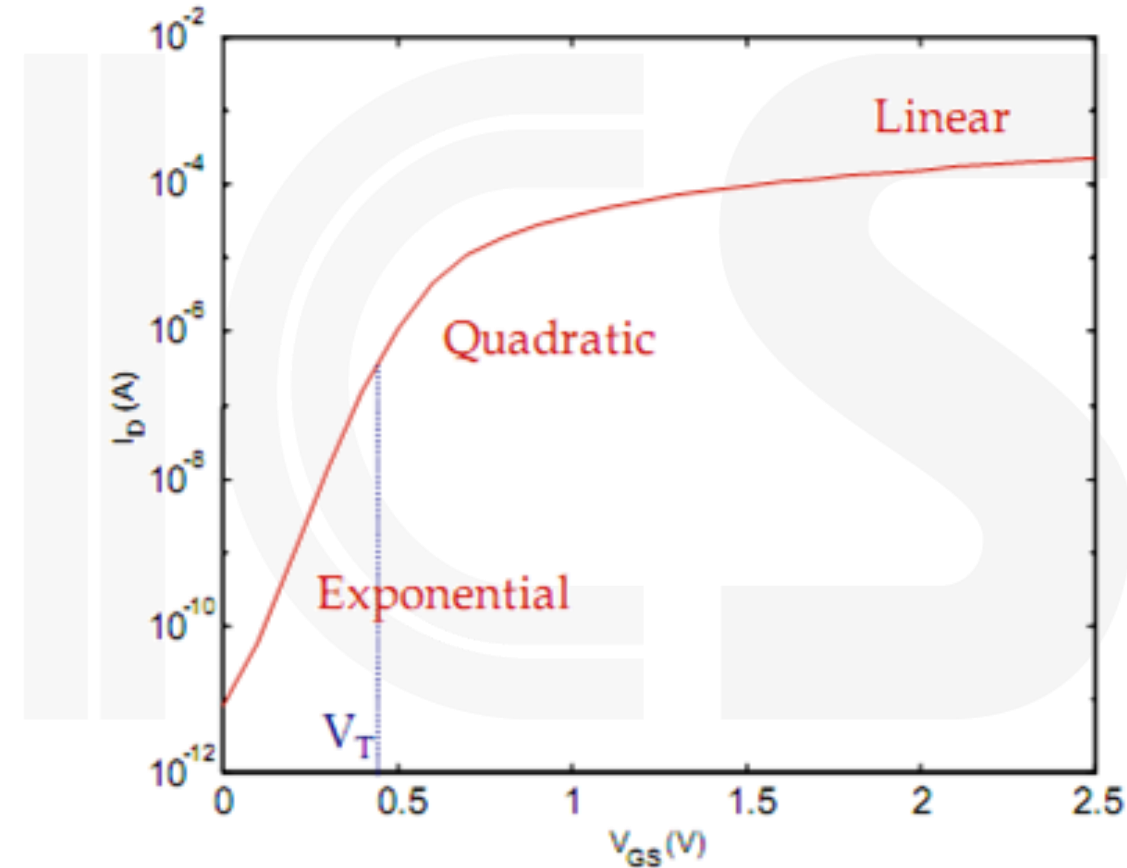
# Subthreshold Leakage

Example:

- We want to design a transistor with:

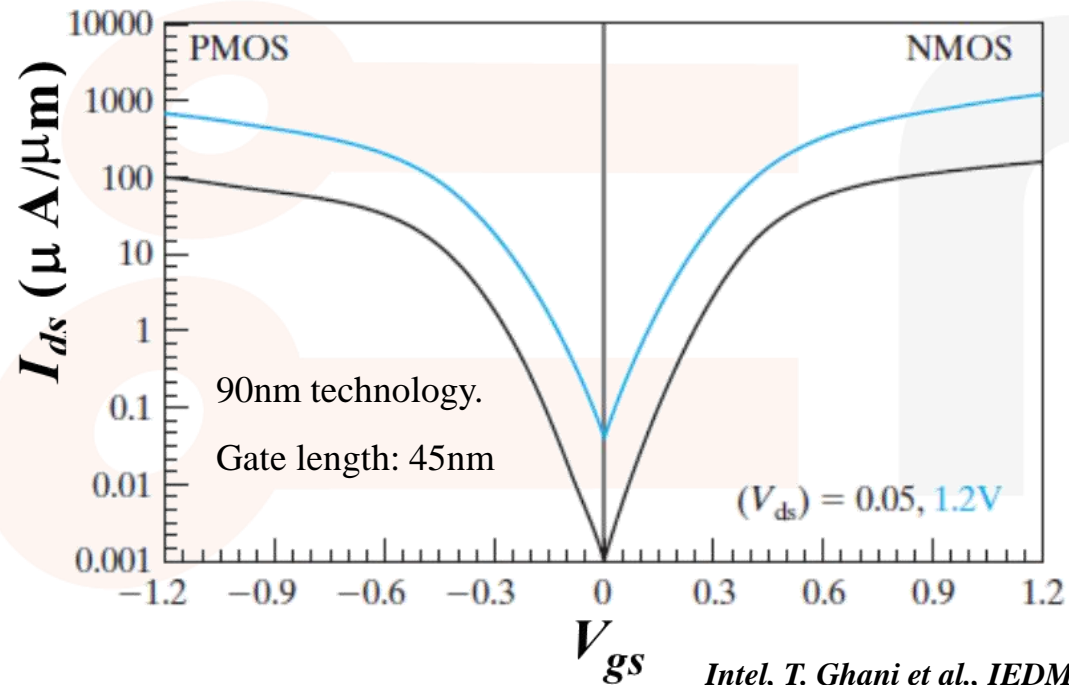
$$\frac{I_{\text{on}}}{I_{\text{off}}} \geq 10^4 \quad S = 60 \frac{\text{mV}}{\text{dec}}$$

- What is the **minimum**  $V_T$ ?



# Impact of DIBL

- **DIBL** causes an additional **exponential** increase in subthreshold leakage with  $V_{DS}$ .



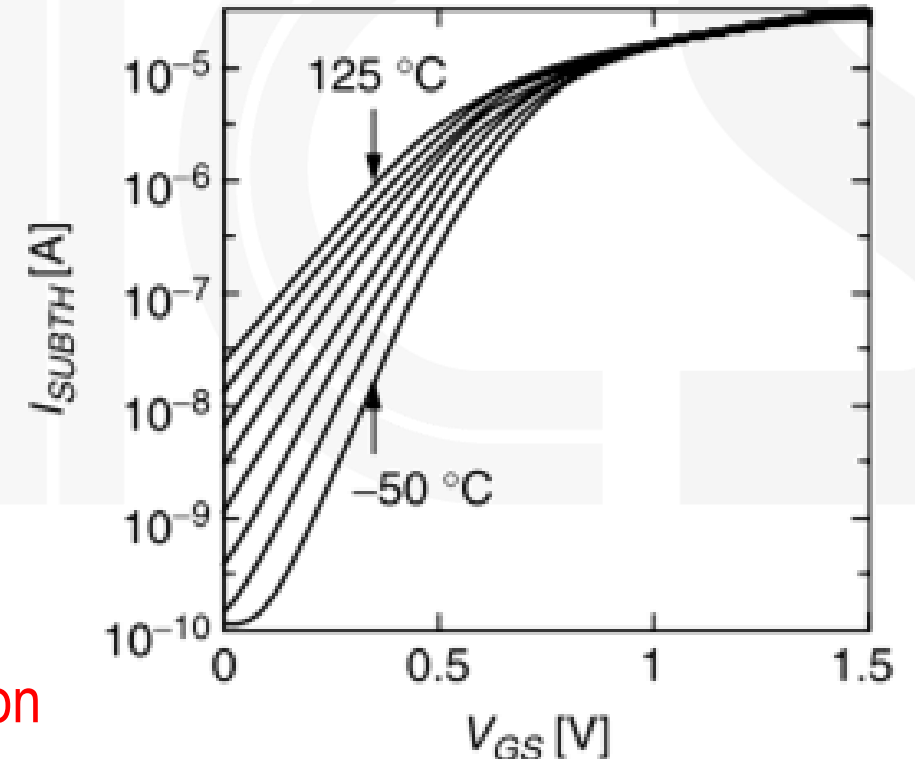
$$I_{\text{sub}} = I_0 e^{\left( \frac{V_{GS} - V_T}{n\phi_T} \right)} \times \left( 1 - e^{\frac{-V_{DS}}{\phi_T}} \right) \times e^{\frac{\eta V_{DS}}{n\phi_T}}$$

# Subthreshold Dependence on Temperature

- This is rather complex, as **mobility degrades** with temperature and **other device values** (such as flatband voltage) are **temperature dependent**.
- Altogether, **subthreshold leakage rises exponentially with temperature\***.

$$I_{\text{sub}} \propto e^{(V_{\text{GS}} - V_{\text{T}}) / \eta \phi_T}$$
$$\phi_T \equiv kT / q$$

\* Without considering temperature inversion





# Temperature Inversion

- Classic approach to temperature effect on delay:

$$\left. \begin{array}{l} I \propto \mu \\ \mu \propto \frac{1}{T} \end{array} \right\} \rightarrow t_{pd} \propto T$$

*So speed decreases with temperature*

$$\left. \begin{array}{l} V_T \propto \frac{1}{T} \\ t_{pd} \propto V_T \end{array} \right\} \rightarrow t_{pd} \propto \frac{1}{T}$$

*So speed actually increases with temperature!*

- BUT!

- $V_T$  decreases by as much as  $-3\text{mV}/^\circ\text{C}$
- The point of *temperature inversion* is the *voltage* at which *speed increases* with temperature ( $\sim V_{DD}=1\text{V}$ )!

# Gate Leakage

- Two mechanisms:

- Direct tunneling (dominant)
- Fowler Nordheim tunneling

- **Exponentially** Dependent on:

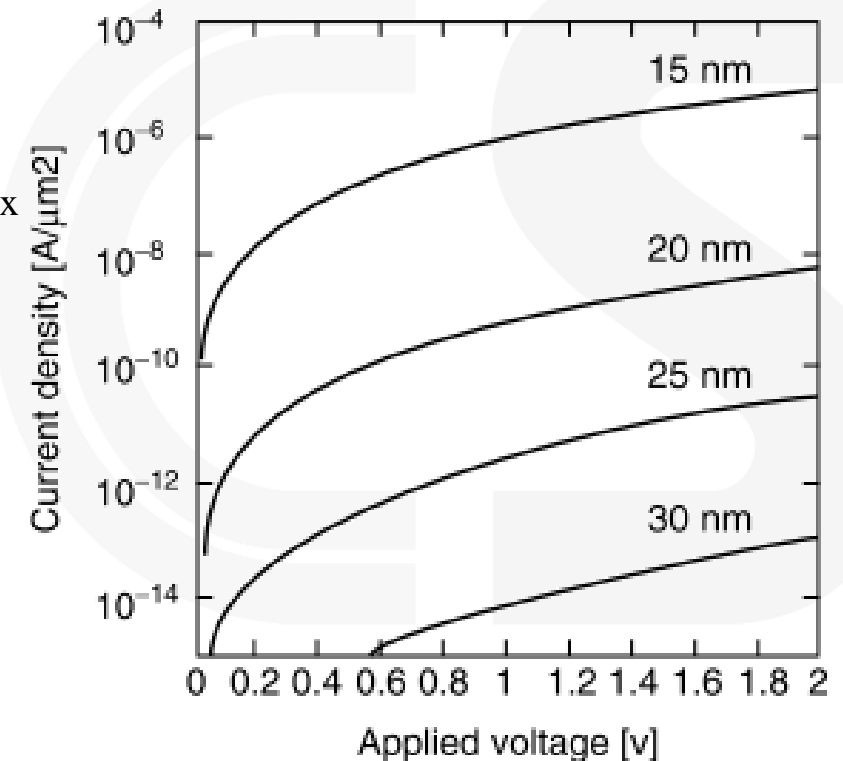
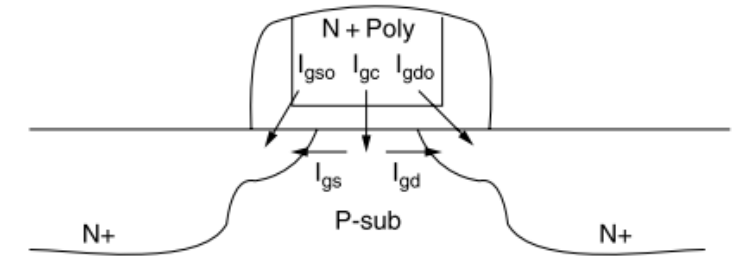
- Gate Voltage ( $V_G$ )
- Oxide Thickness ( $t_{ox}$ ).

- Non-dependent on temperature.

- Much stronger in nMOS than pMOS

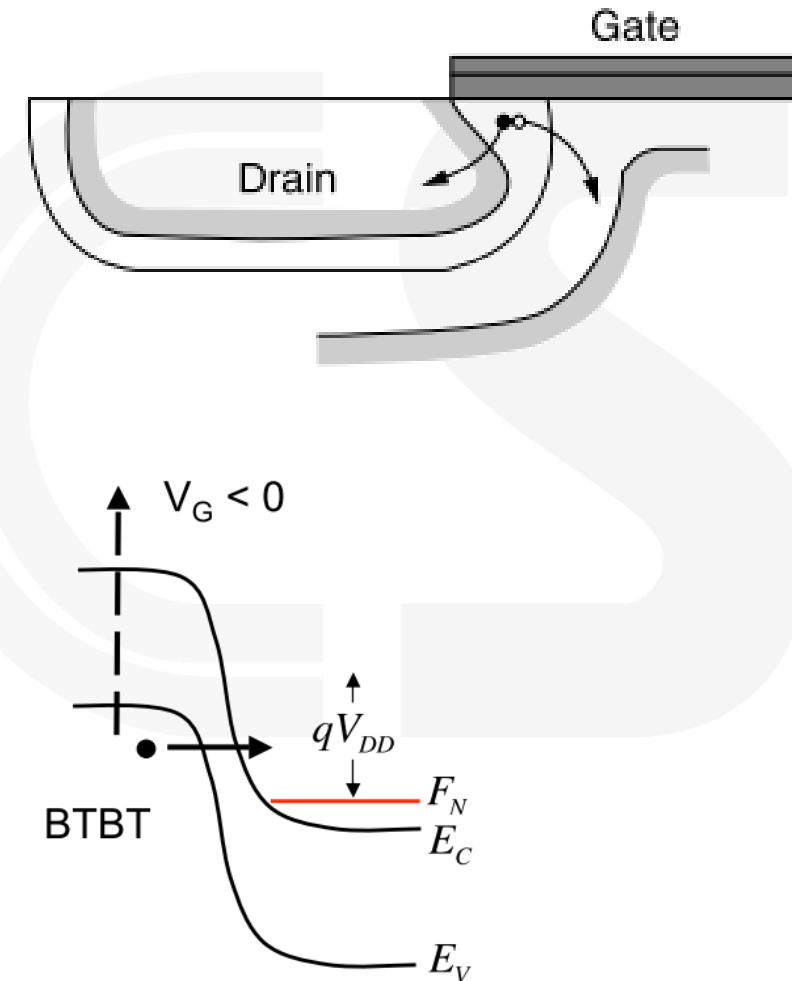
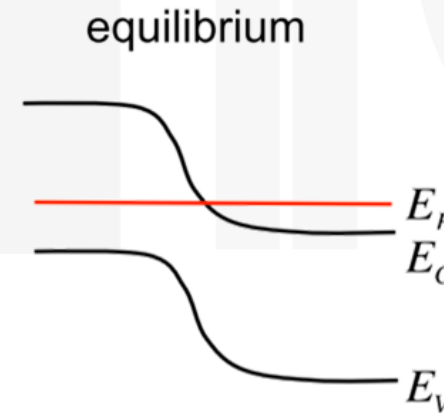
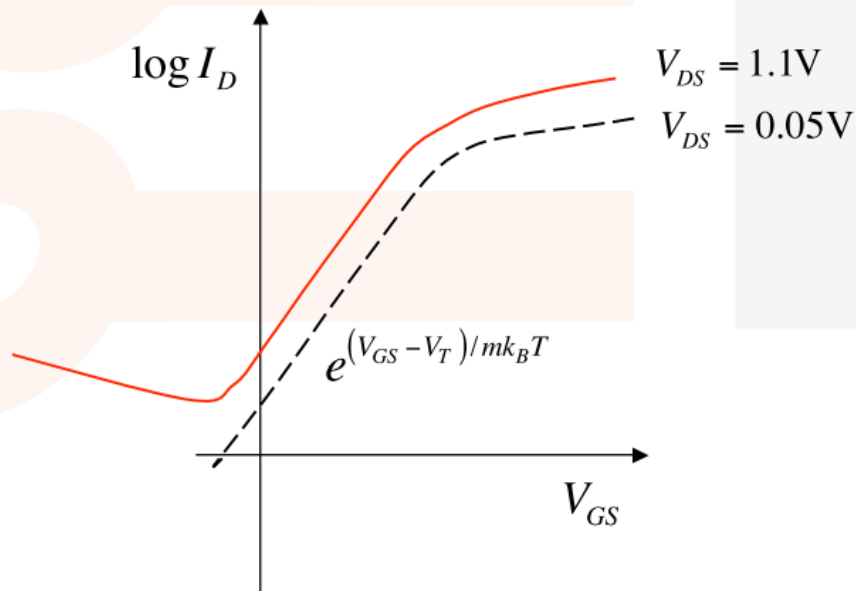
(higher barrier for holes)

- Minimum  $t_{ox}=1.2\text{nm}!!!$



# Gate Induced Drain Leakage

- **GIDL** current flows from the drain to the substrate.
- Caused by high electric field **under the gate/drain overlap**, causing *e-h pair* creation.
- Main phenomena is **Band-to-Band Tunneling**

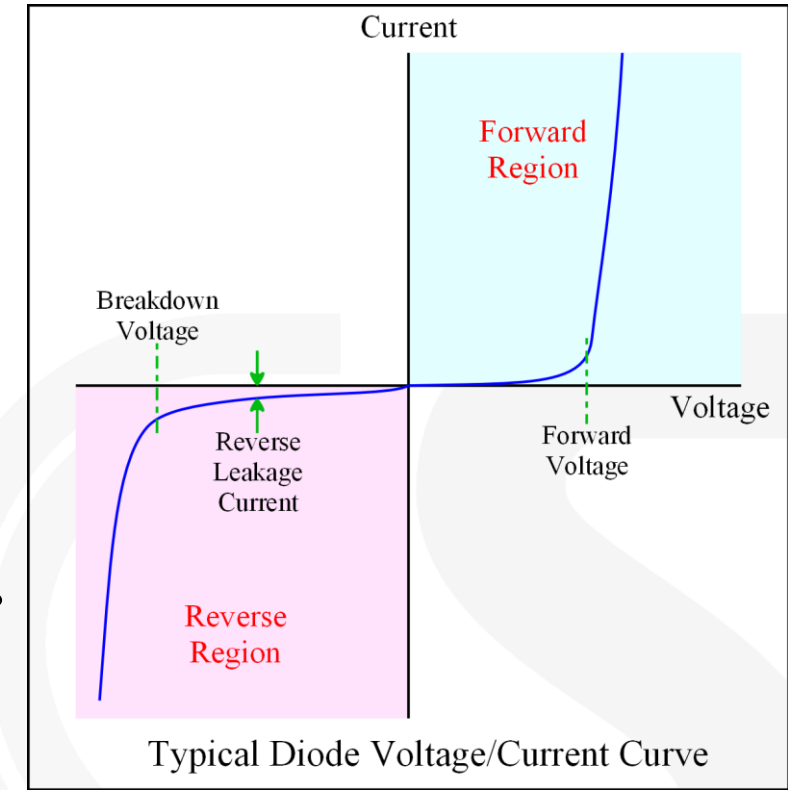


# Diode Leakage

- $J_S = 10\text{-}100\text{pA}/\mu\text{m}^2$  @  $25^\circ\text{C}$  for  $0.25\mu\text{m}$  CMOS.
- $J_S$  doubles for every  $9^\circ\text{C}$

$$I_{\text{DL}} = J_S \times A$$

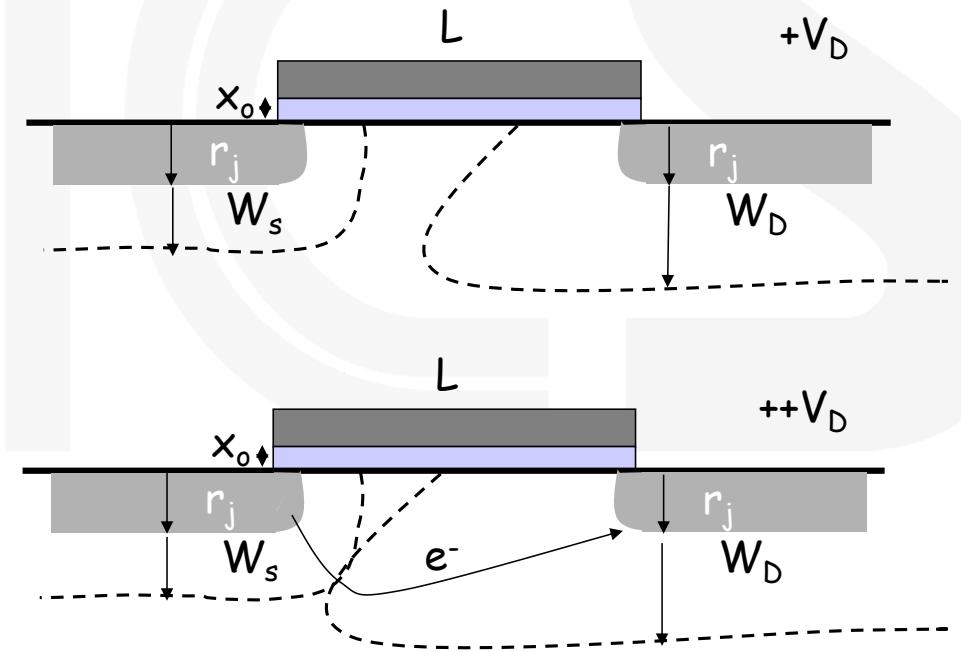
- Much smaller than other leakages in deep sub-micron.
  - But a bigger factor in low subthreshold leakage processes, like FinFET.



Source: cmicrotek.com

# Punchthrough

- As  $V_{DS}$  grows, so does the **drain depletion region**, and the **channel length decreases**.
- In severe cases, the **source and drain are connected** causing **non-controllable leakage current**.



# Leakage Summary

- **Subthreshold Leakage:**

- $I_{DS} > 0$  when  $V_{GS} < V_T$  due to **weak inversion**.
- Grows with  $V_{GS}$ ,  $V_{DS}$ , lower  $V_T$

- **Gate Leakage:**

- $I_G > 0$  due to **direct tunneling** through the oxide.
- Grows with  $V_{GB}$ ,  $t_{ox}$

- **Gate Induced Drain Leakage (GIDL):**

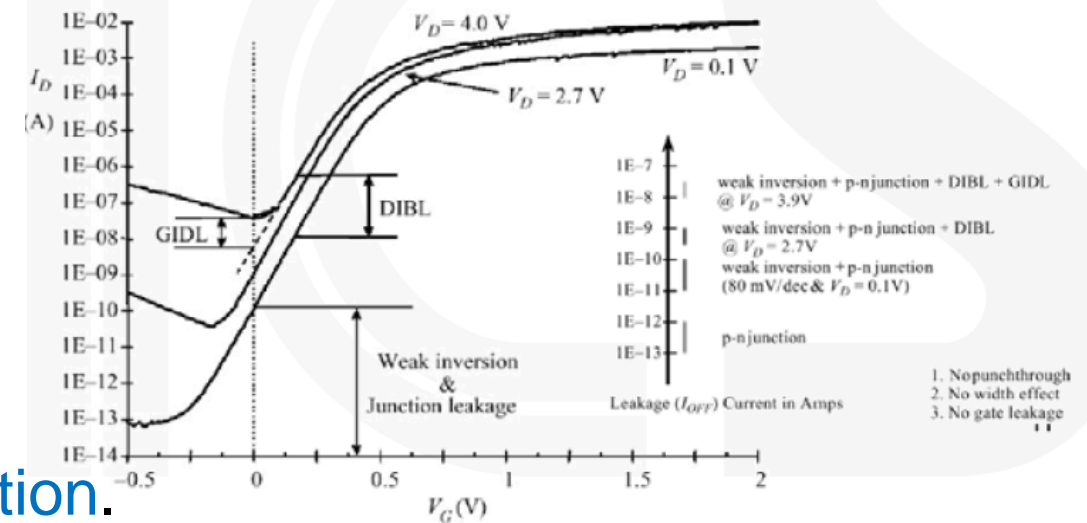
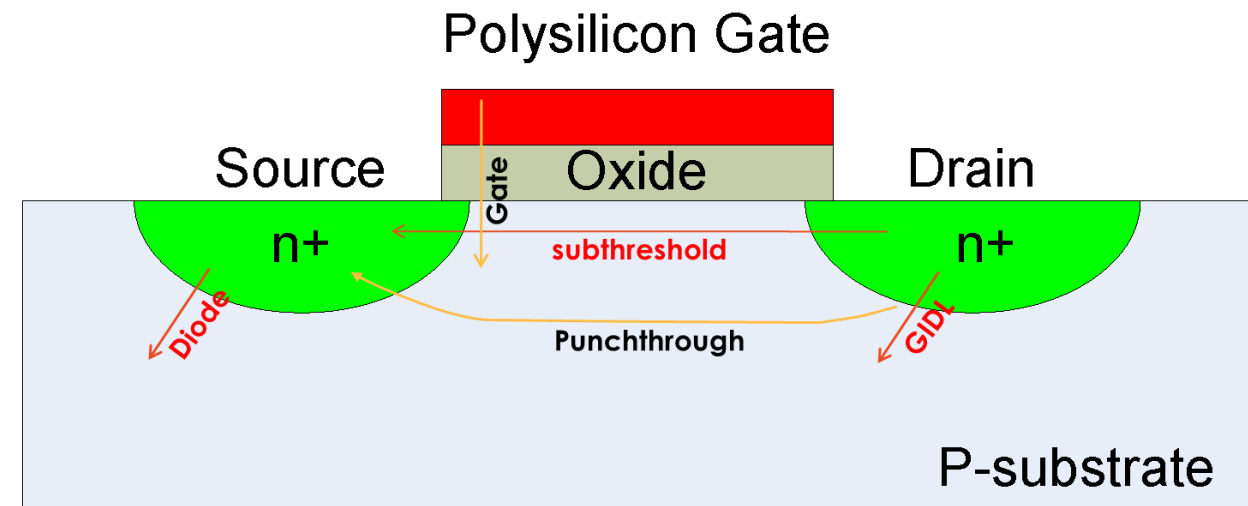
- $I_{DB} > 0$  due to **high electric field** in the GD overlap region ( $V_{GD}$ ).

- **Reverse Biased Diode Leakage**

- $I_{SB}$ ,  $I_{DB}$  due to diffusion and thermal **generation**.

- **Punchthrough:**

- $I_{DS}$  due to drain and source **depletion layers** touching.



[IEEE press, 2000]

# Process Corners - Revisited

- Should we now redefine the **PVT** settings?

*But what about  
Temperature Inversion?*

Corner	$V_T$	$L_{\text{eff}}$	$t_{\text{ox}}$	$V_{DD}$	$T$
Fast	↓	↓	↓	↑	↓
Typical	X	X	X	X	X
Slow	↑	↑	↑	↓	↑
Max Leakage	↓	↓	↓↑	↑	↑

# Further Reading

- J. Rabaey, “Digital Integrated Circuits” 2003, Chapters 2.5, 3.3-3.5
- Weste, Harris “CMOS VLSI Design”, Chapter 7
- C. Hu, “Modern Semiconductor Devices for Integrated Circuits”, 2010, Chapters 4-7
- Tzividis, et al. “Operation and Modeling of MOS Transistor” Chapters 1-5
- E. Alon, Berkeley EE-141, Lecture 9 (Fall 2009)
- M. Alam, Purdue ECE-606 – lectures 32-38 (2009) nanohub.org
- A. B. Bhattacharyya “Compact MOSFET models for VLSI design”, 2009,
- T. Sakurai, “Alpha Power-Law MOS Model” – JSSC Newsletter Oct 2004
- Managing Process Variation in Intel’s 45nm CMOS Technology, Intel Technology Journal, 2008
- Berkeley “BSIM 4.6.4 User’s Manual”  
[http://www-device.eecs.berkeley.edu/~bsim/BSIM4/BSIM464/BSIM464\\_Manual.pdf](http://www-device.eecs.berkeley.edu/~bsim/BSIM4/BSIM464/BSIM464_Manual.pdf)